

How to Design an Integrated Circuit

IC *design* is detailed and meticulous (i.e. not cheap)
IC *fabrication* is also not cheap
No user serviceable parts inside – the chip works or it doesn't

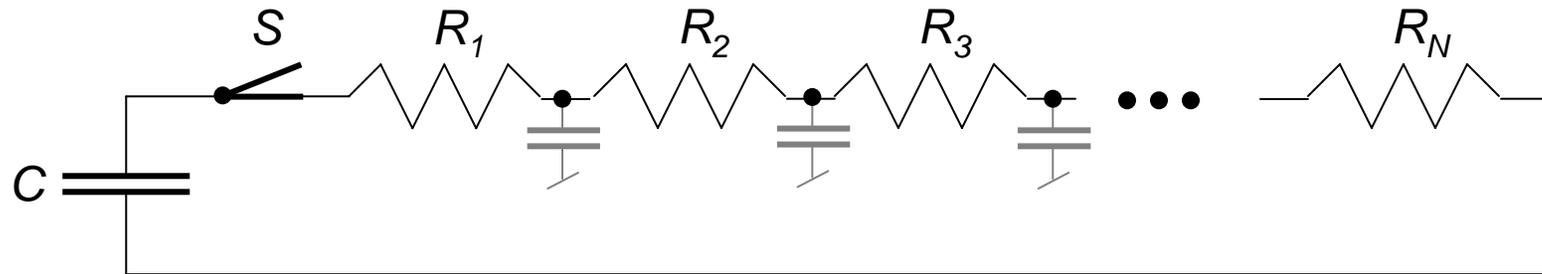
So why do we do this at LBL?
Is IC design really sorcery?

- ◆ History and Motivation
 - What's a circuit
 - What's an integrated circuit
- ◆ IC design process
- ◆ Our friend the MOS transistor
- ◆ Let's make a chip
- ◆ Examples
- ◆ Trends

P. Denes
Engineering Division



Circuit Problem ca. 1750



Charge capacitor **C**

Close switch **S**

Estimate propagation time through this transmission line

$N \sim 1000$



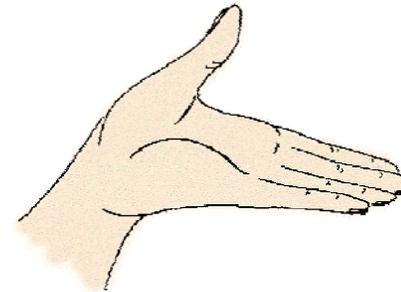
Solution



$R_1 \dots R_{1000}$



C



S

French physicist Abbe Nollet

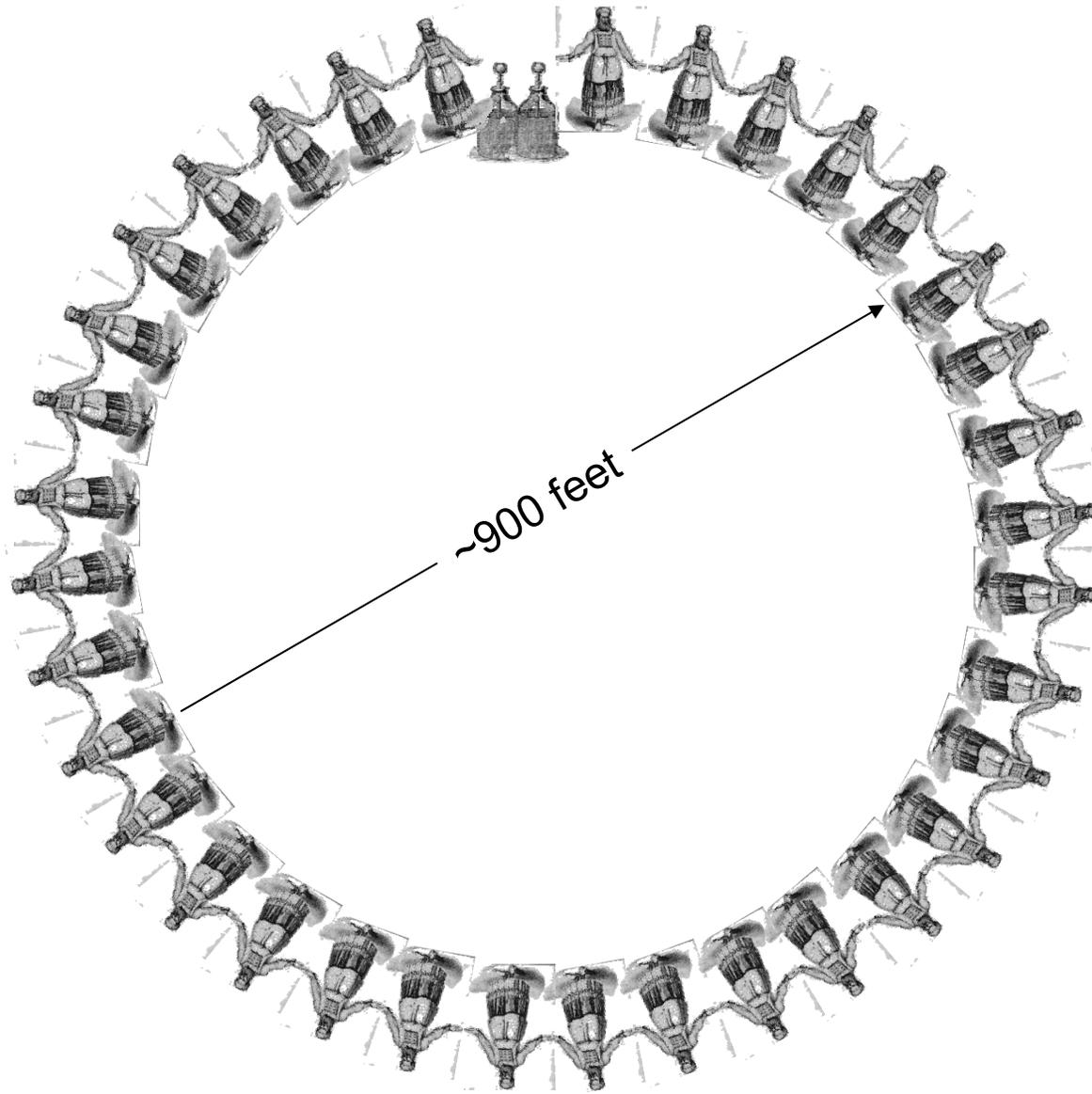
Components used:

1000 Carthusian monks

Capacitor based on design from University of Leyden

Resistive contact to C

Circuit Layout

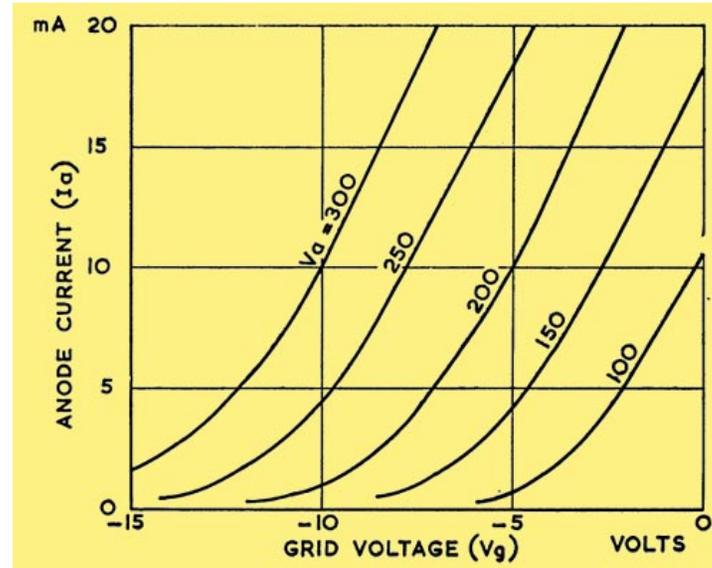
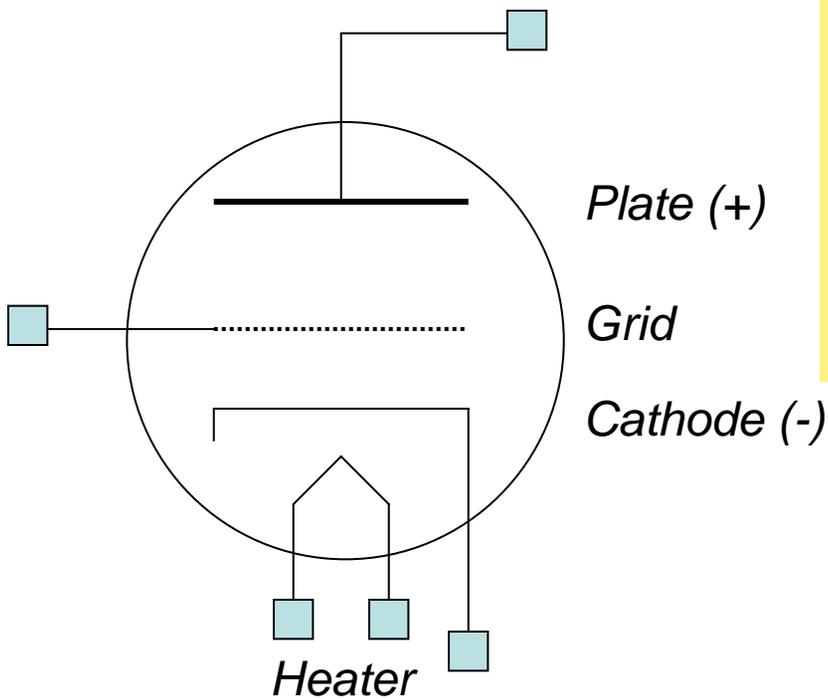


- ◆ Simultaneous jumping of monks → “electricity is fast”
- ◆ Circuit composed of well-defined, discrete parts connected together
- ◆ (Circuit dimensions are a bit large)



Fast Forward → 1906

Triode
Lee de Forest



- ◆ Grid modulates conduction
- ◆ Can be used for analog applications
- ◆ Can also be used for digital applications

ENIAC – 1945, U. Penn.



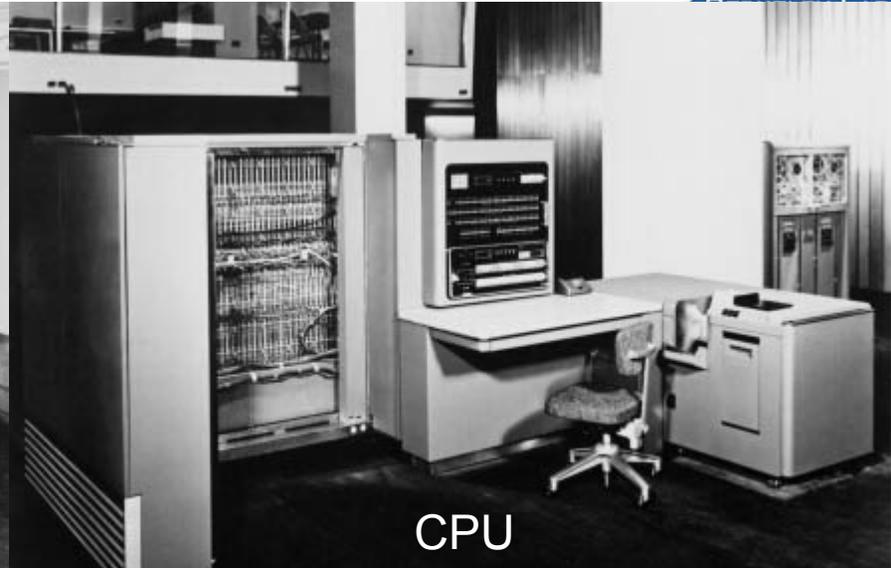
Designed to calculate ballistic ordnance firing tables
Electronic Numerical Integrator And Computer



Its thirty separate units, plus power supply and forced-air cooling, weighed over thirty tons. Its 19,000 vacuum tubes, 1,500 relays, and hundreds of thousands of resistors, capacitors, and inductors consumed almost 200 kilowatts of electrical power.

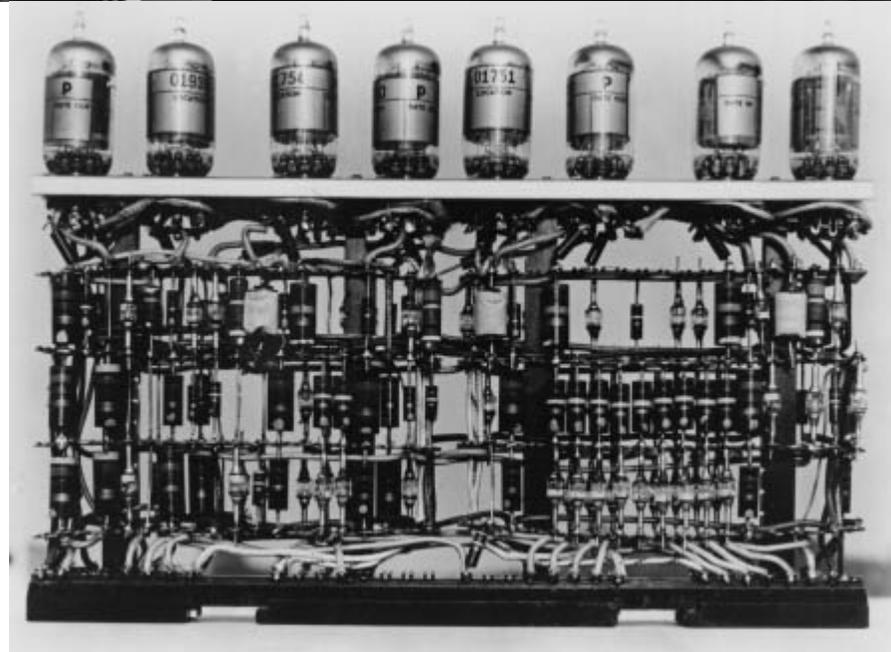


IBM 701 - 1952

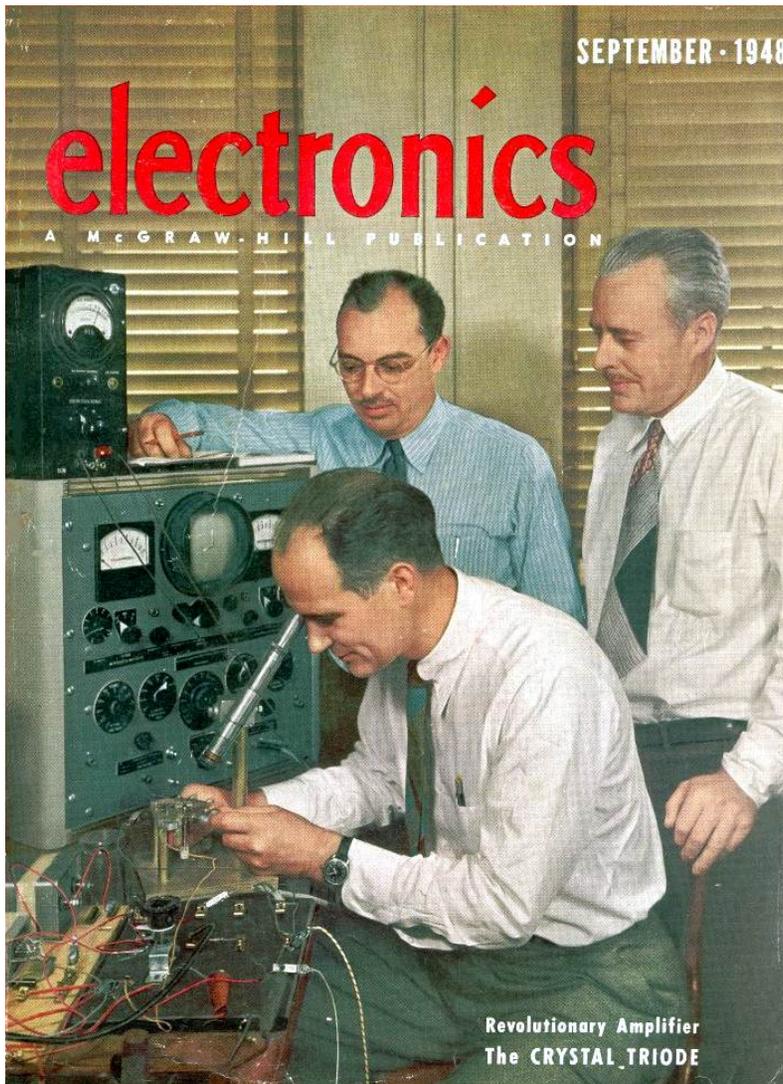


16 kHz cycle
2k words fast storage
1st computer for scientific work

**Modular circuit assemblies
of components**

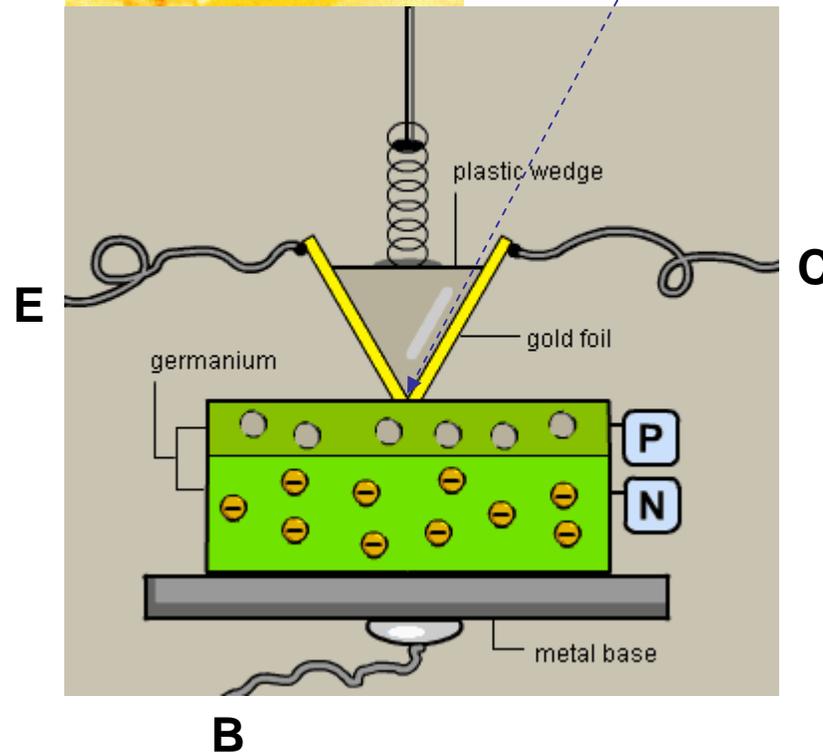


The solution?



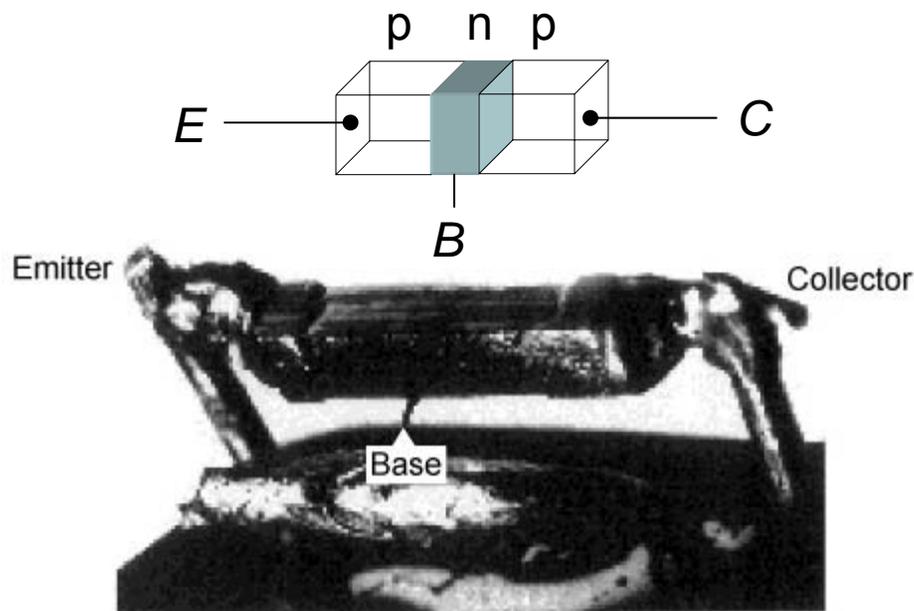
Point contact transistor

Thin razor cut



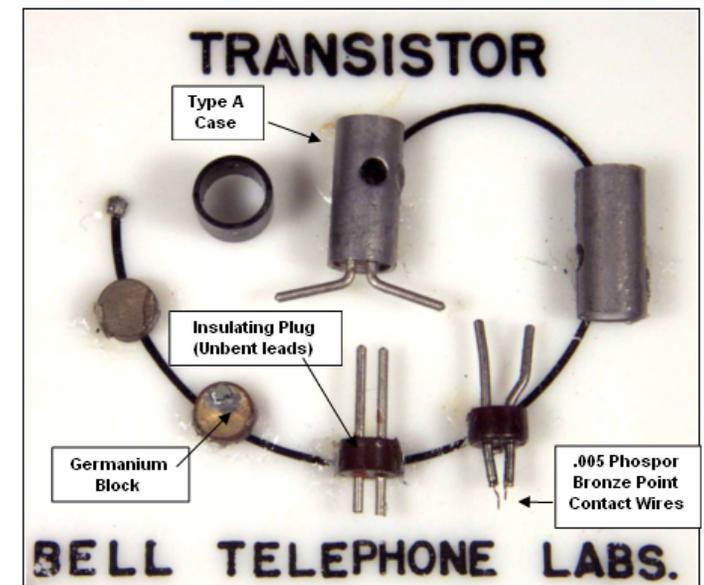
Almost

- ◆ Point contact transistor is a surface effect device (and surfaces are easy to contaminate – not to mention paper clips can be mechanically unstable)
- ◆ Schottky contacts, rather than pn junctions
- ◆ Shockley junction transistor (1949)



Ge

Although the point contact transistor did live for a while



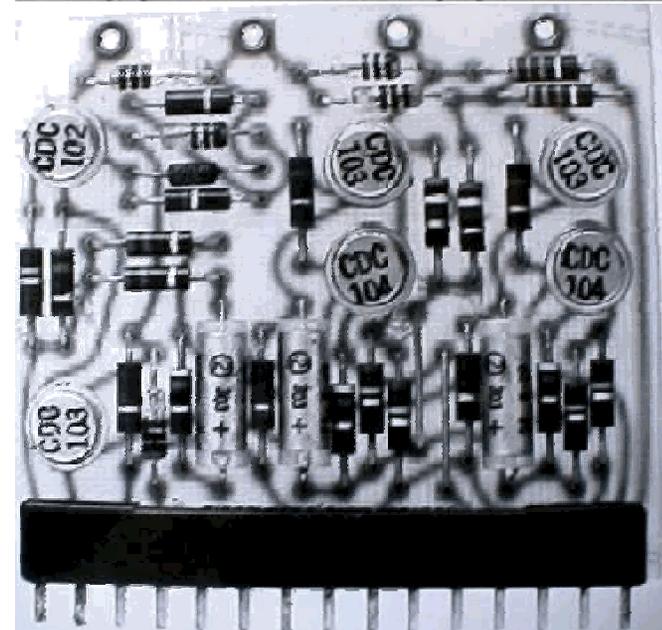
CDC 1604/160 - 1960



160 kHz cycle
32k words fast storage

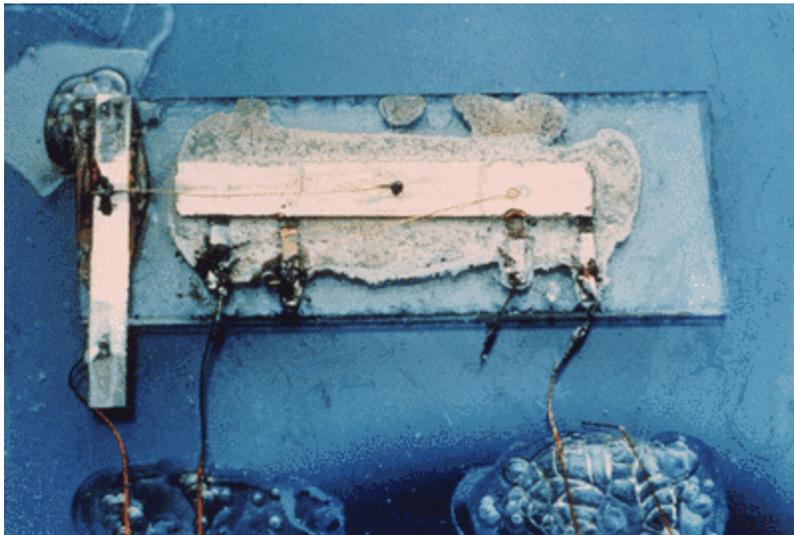
**Modular circuit assemblies
of components**

The first desktop (literally)

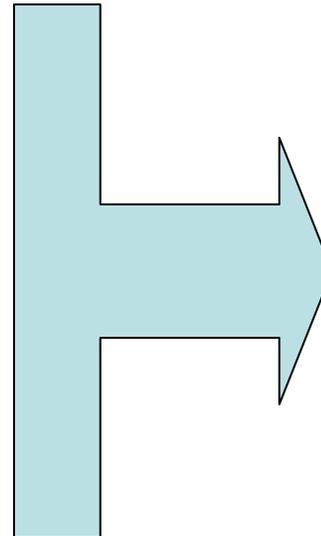


Integrated Circuits - 1958

Jack Kilby
Ge
(1 transistor)



Texas Instruments
(Patent)



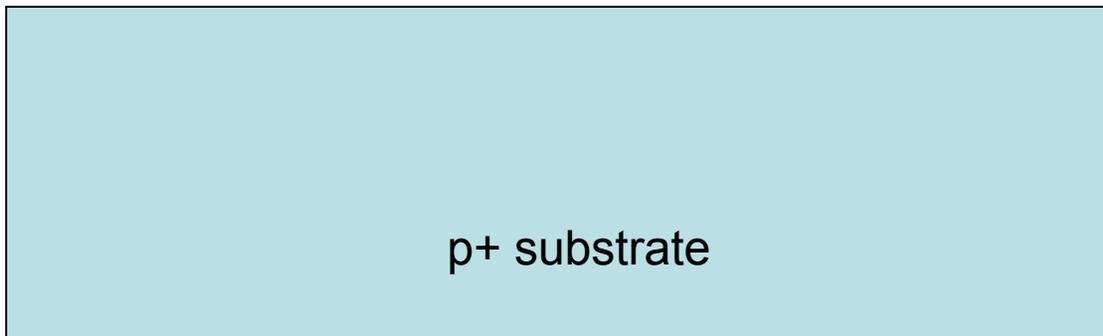
Legal wrangles
Resolved in mid-60's

Robert Noyce
Si
(2 transistors)

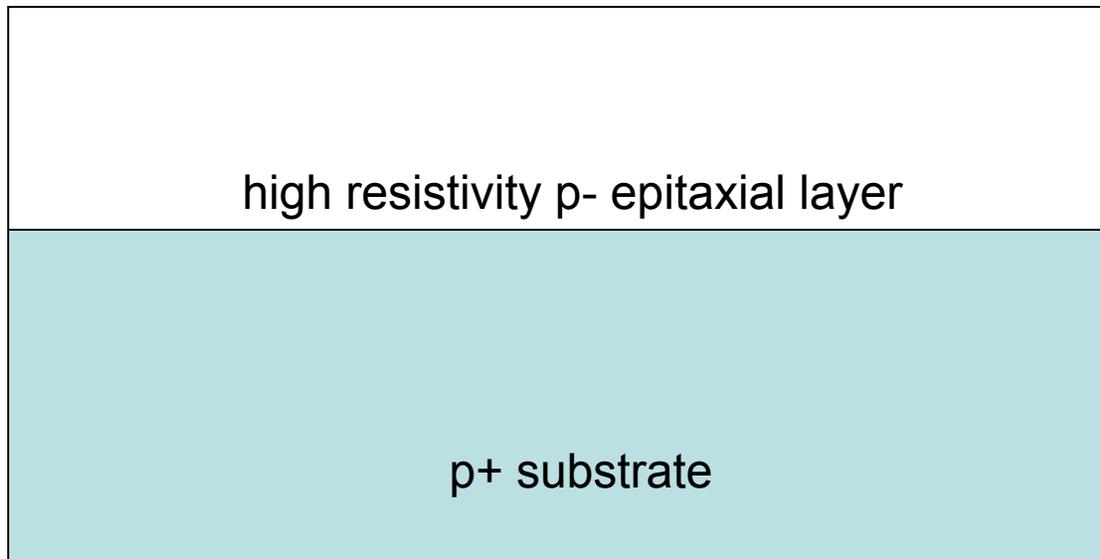
Fairchild
(Patent)



Early Circuits – Planar Bipolar Process



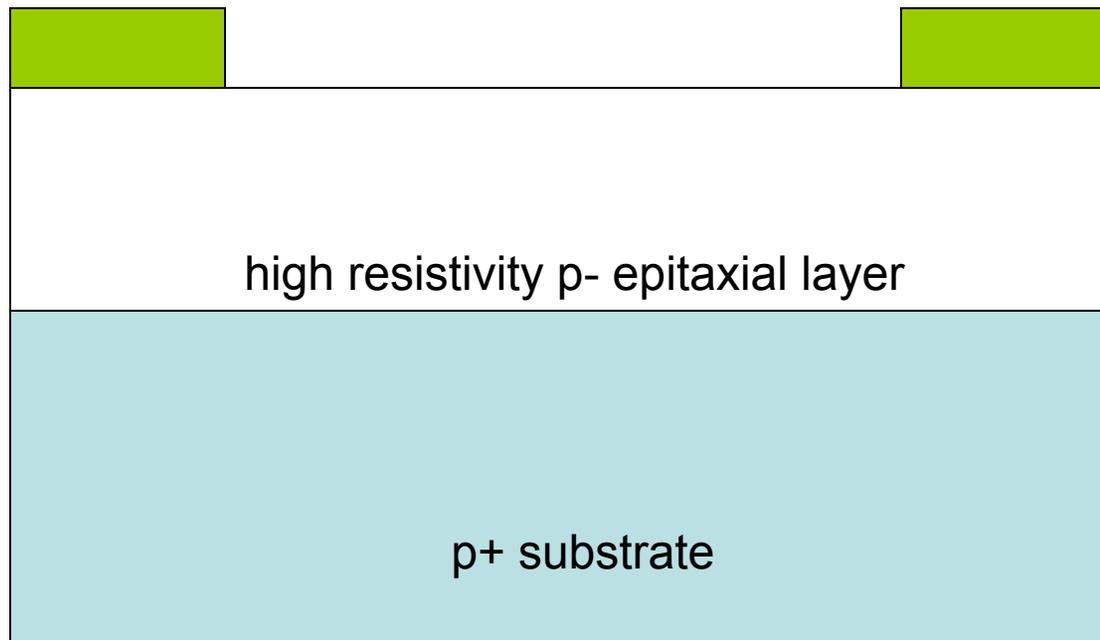
Early Circuits – Planar Bipolar Process



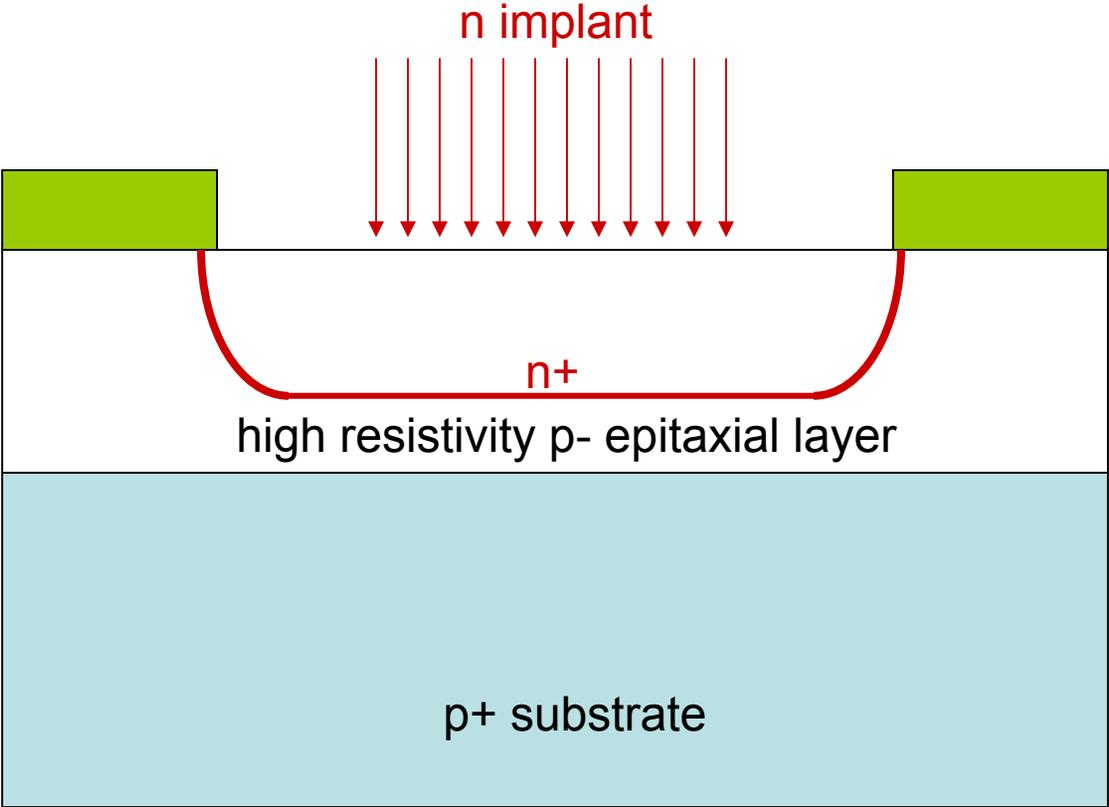
Early Circuits – Planar Bipolar Process



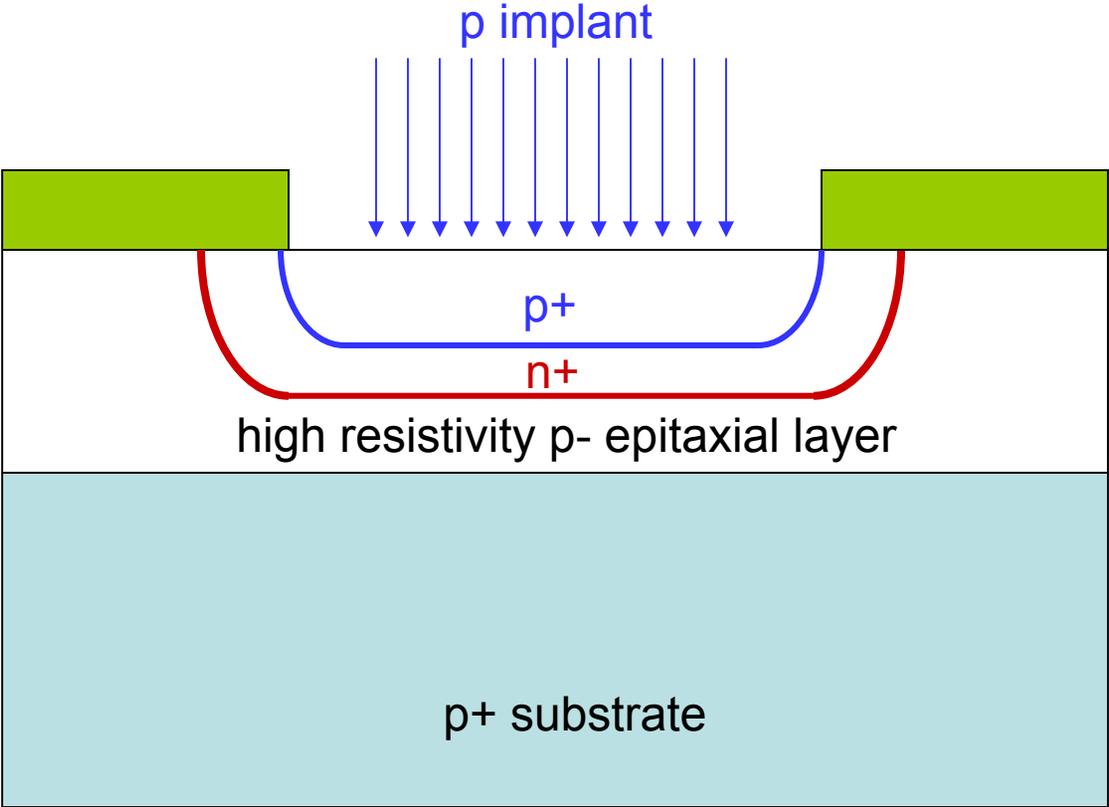
grow SiO_2 and
open base window



Early Circuits – Planar Bipolar Process



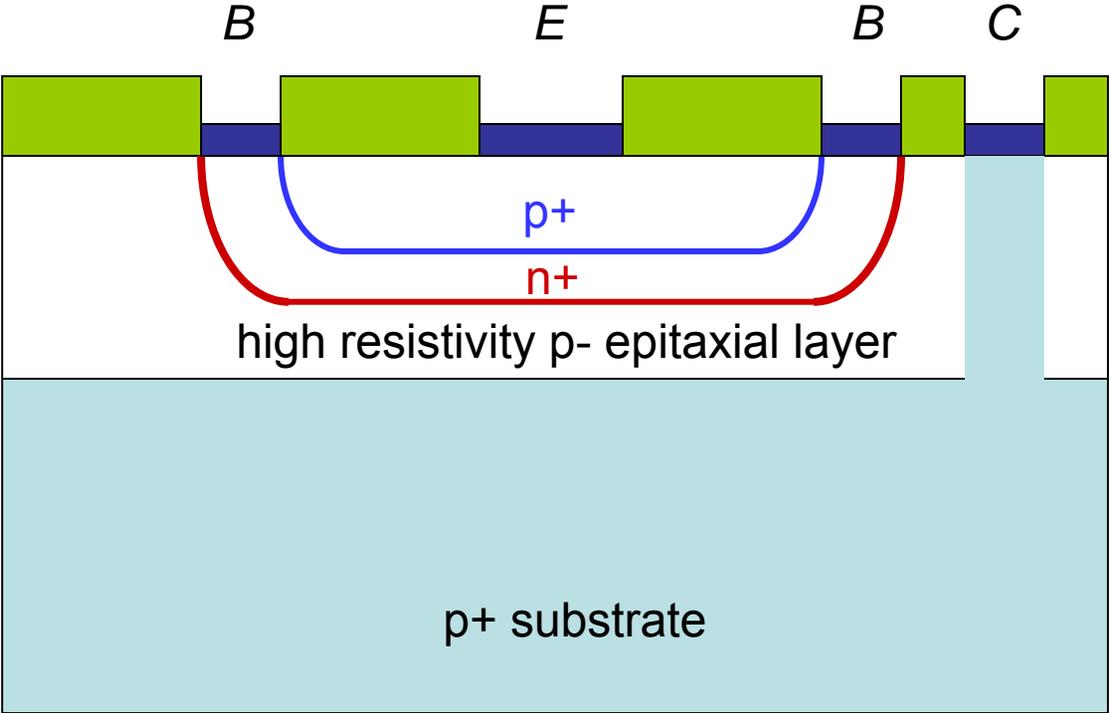
Early Circuits – Planar Bipolar Process



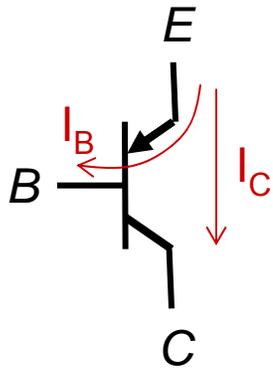
Early Circuits – Planar Bipolar Process



Contacts/Metal

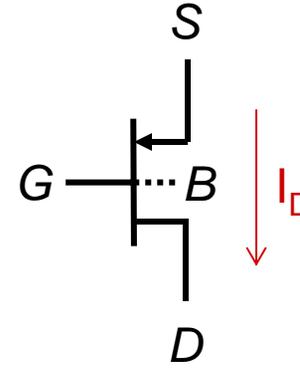


Bipolar Junction vs. Insulated Gate Transistors



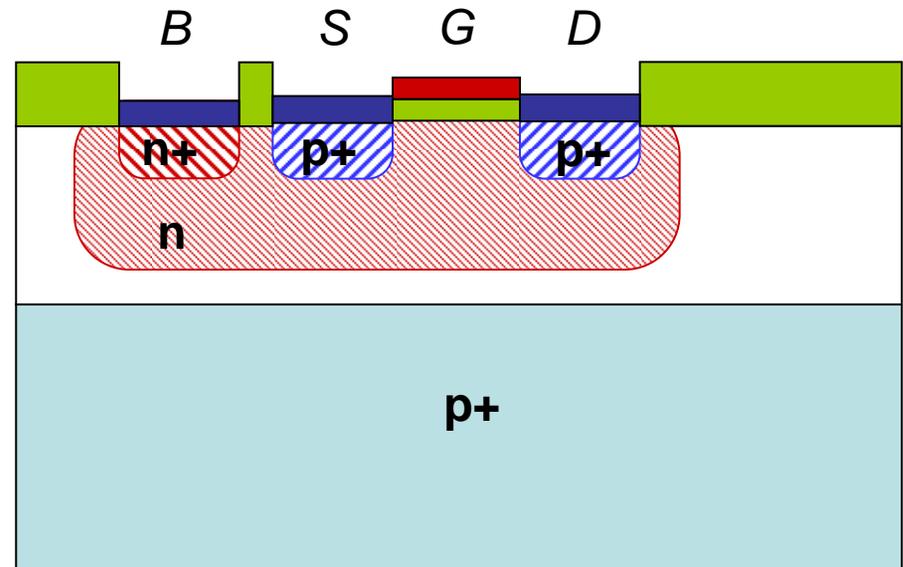
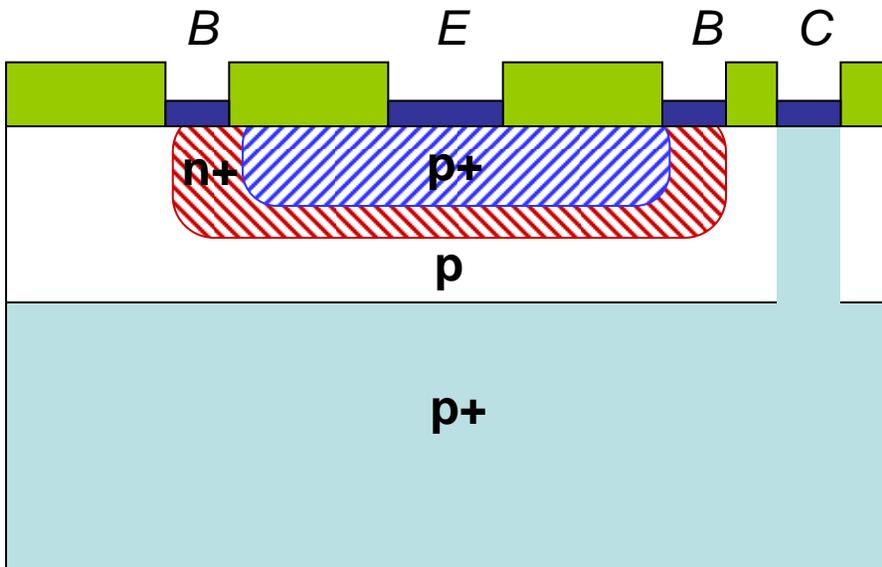
$$I_C \sim \beta I_B$$

$$I_B \sim \exp(V_{BE}/kT)$$



$$I_D \sim (V_{GS} - V_T)^2 \quad V_{GS} > V_T$$

$$I_D \sim 0 \quad V_{GS} < V_T$$

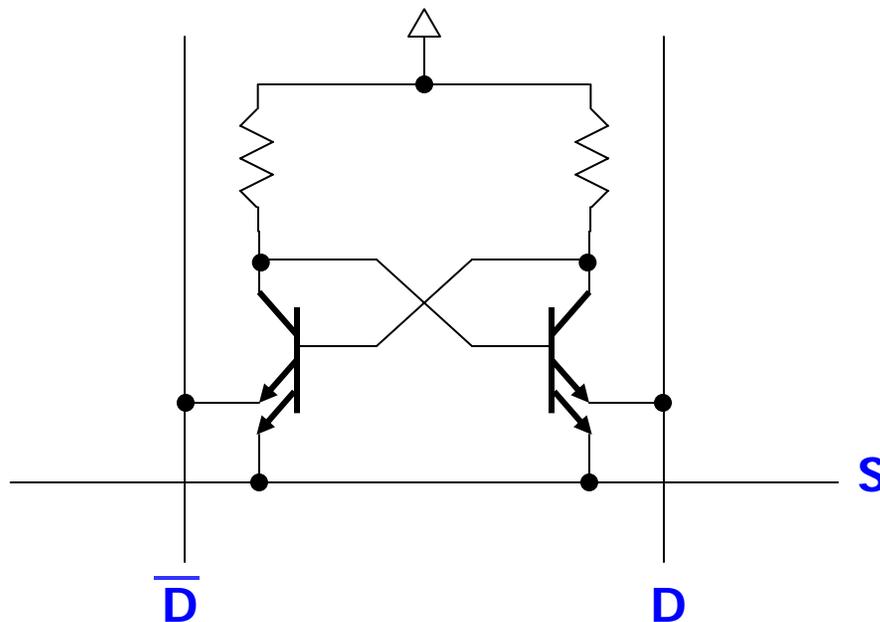


1st MOS on Si - 1960

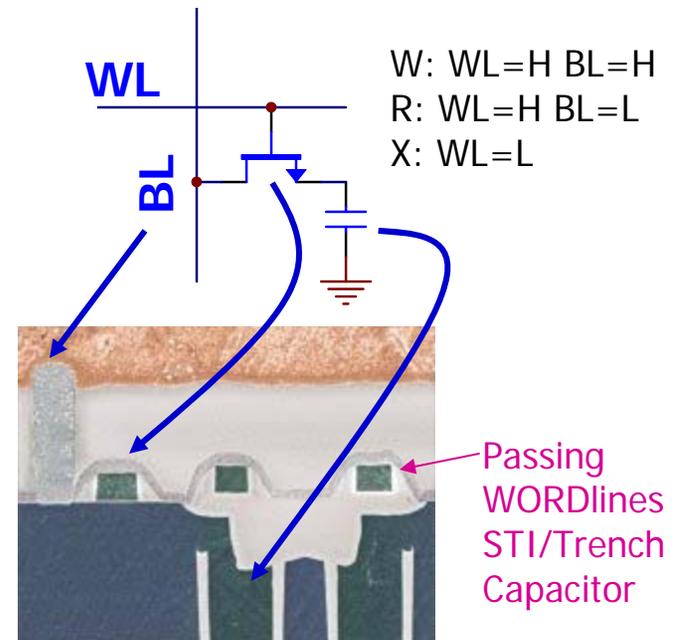
MOS and CMOS take over

- ◆ Early circuits were mostly bipolar (especially analog)
- ◆ MOS took hold for memory
- ◆ CMOS invented in 1963, but took off (once fabrication became good enough) in the 80's

Bipolar SRAM



CMOS DRAM

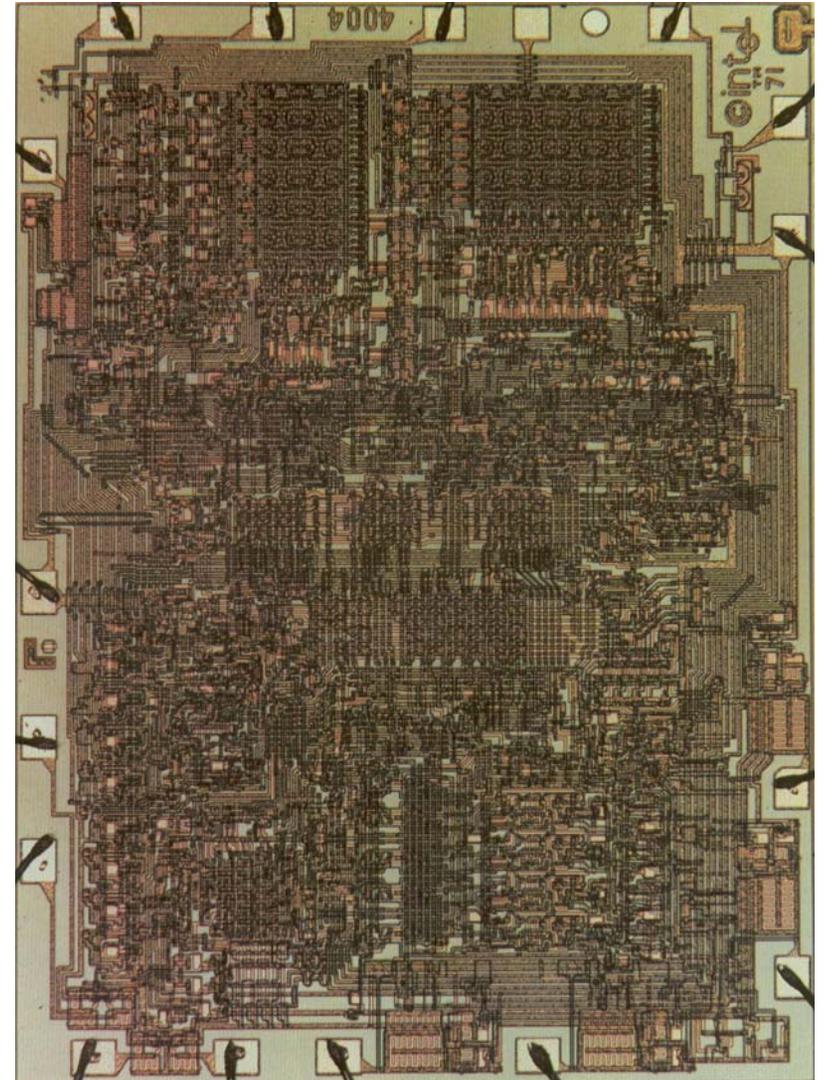


MOS logic – Intel 4004 - 1970

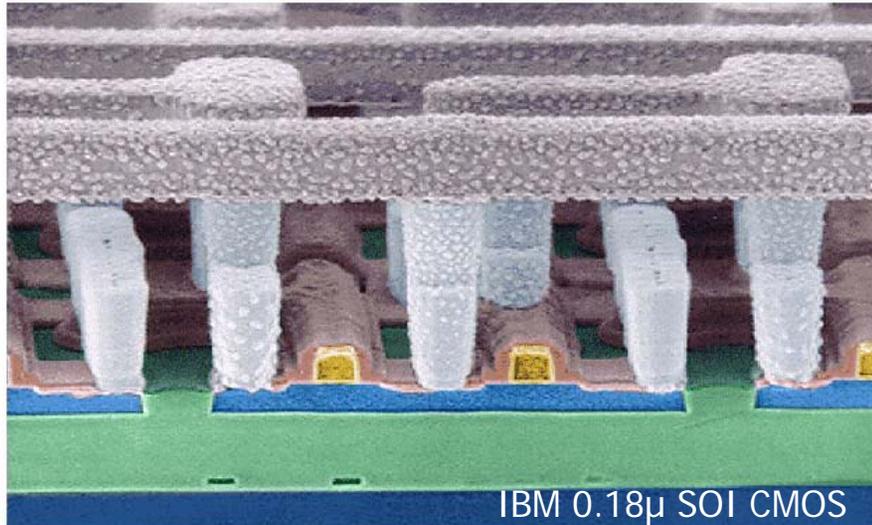
8 μ m PMOS

The first single chip CPU was the Intel 4004, a 4-bit processor meant for a calculator. It processed data in 4 bits, but its instructions were 8 bits long. Program and Data memory were separate, 1K data memory and a 12-bit PC for 4K program memory (in the form of a 4 level stack, used for CALL and RET instructions). There were also sixteen 4-bit (or eight 8-bit) general purpose registers.

The 4004 had 46 instructions, using only 2,300 transistors in a 16-pin DIP. It ran at a clock rate of 740kHz (eight clock cycles per CPU cycle of 10.8 microseconds) - the original goal was 1MHz, to allow it to compute BCD arithmetic as fast (per digit) as a 1960's era IBM 1620.



Timeout - Glossary



Metal Interconnect

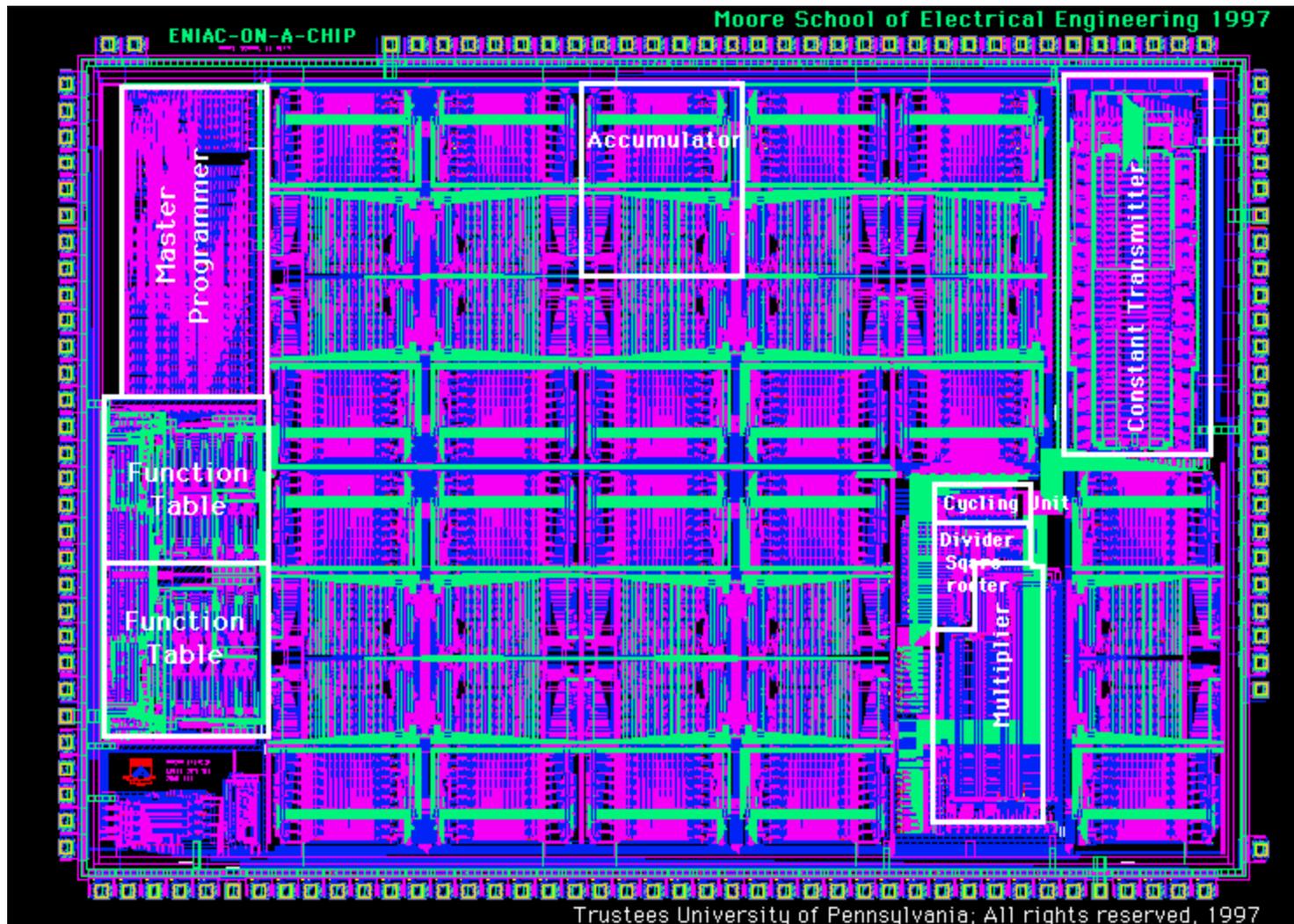
Metal Interconnect

Polysilicon gate

Process – the complete fabrication process which produces the integrated circuits. It includes photolithographic mask preparation, wafer preparation and processing, etc. The *process* defines for the designer what kinds of devices are available and what their performance characteristics should be

Feature size (or line width) – the smallest dimension which can be reliably lithographed. So a “1 μm CMOS process” contains N- and P-channel MOS transistors with 1 μm minimum feature size

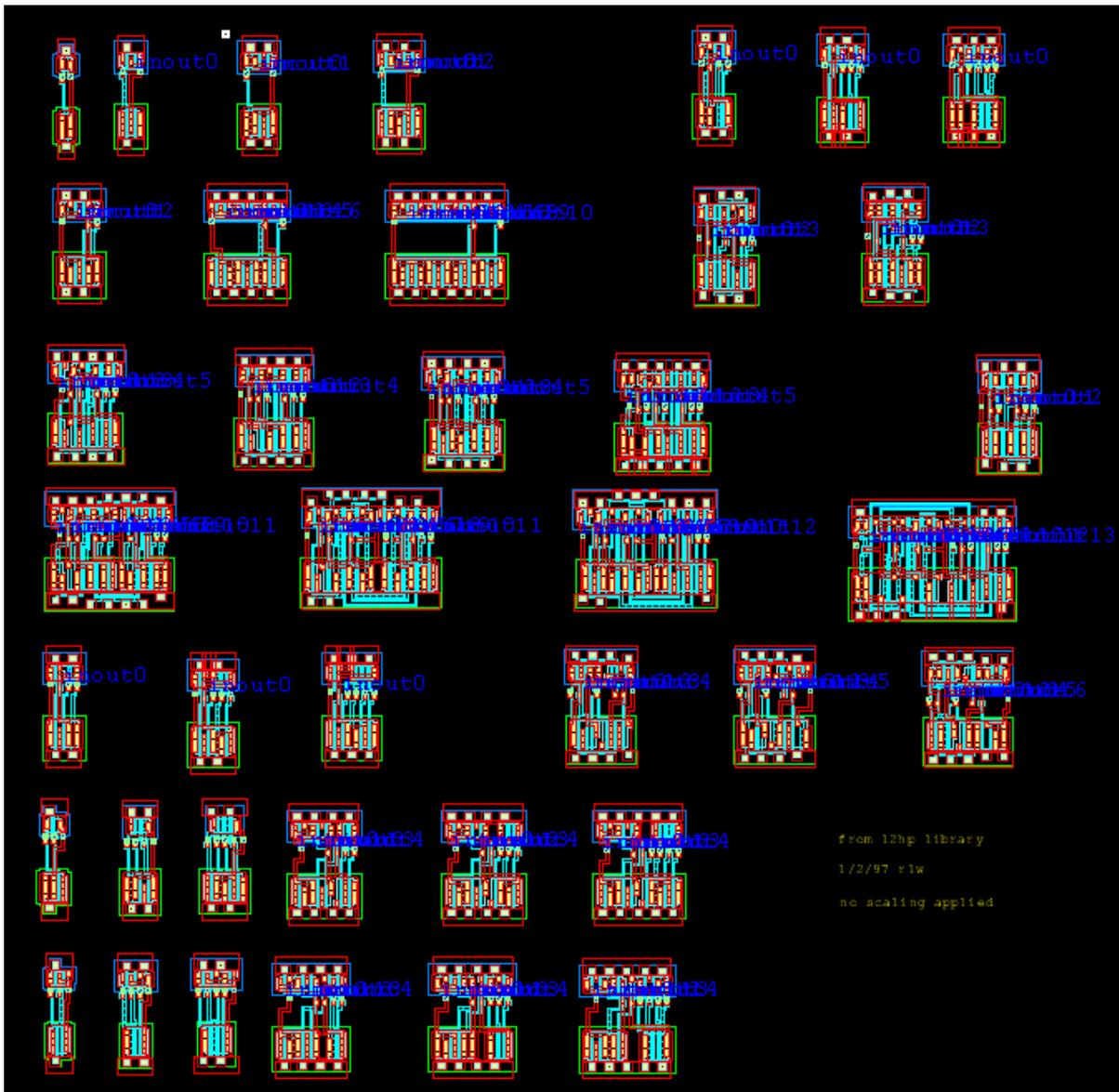
ENIAC – 50th Anniversary Edition



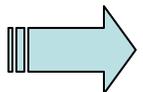
Size: 7.44mm x 5.29mm; 174,569 transistors; 0.5 um CMOS technology (triple metal layer).

30 mg vs 30 tons

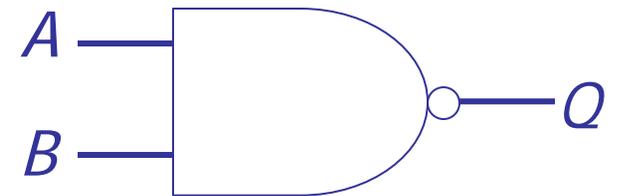
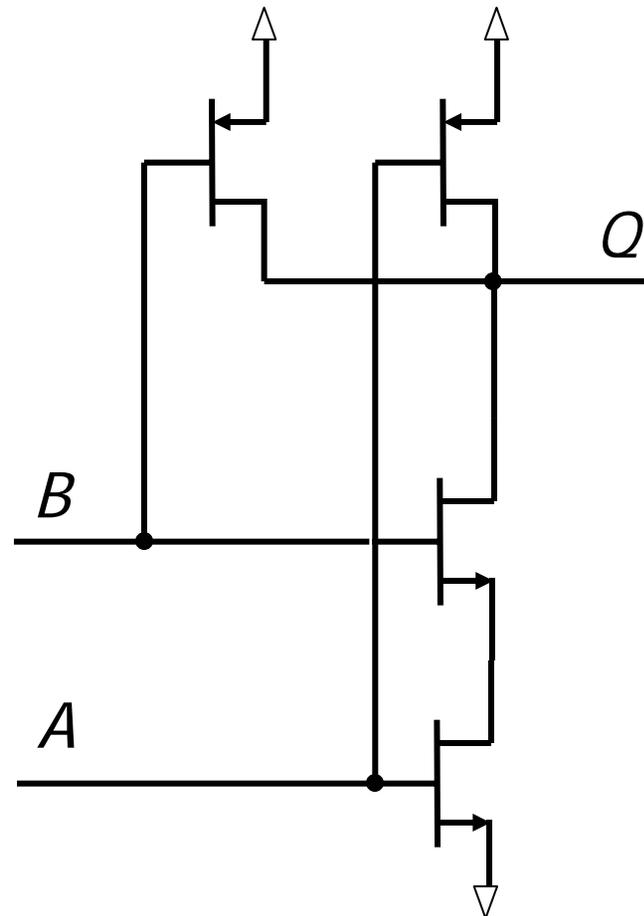
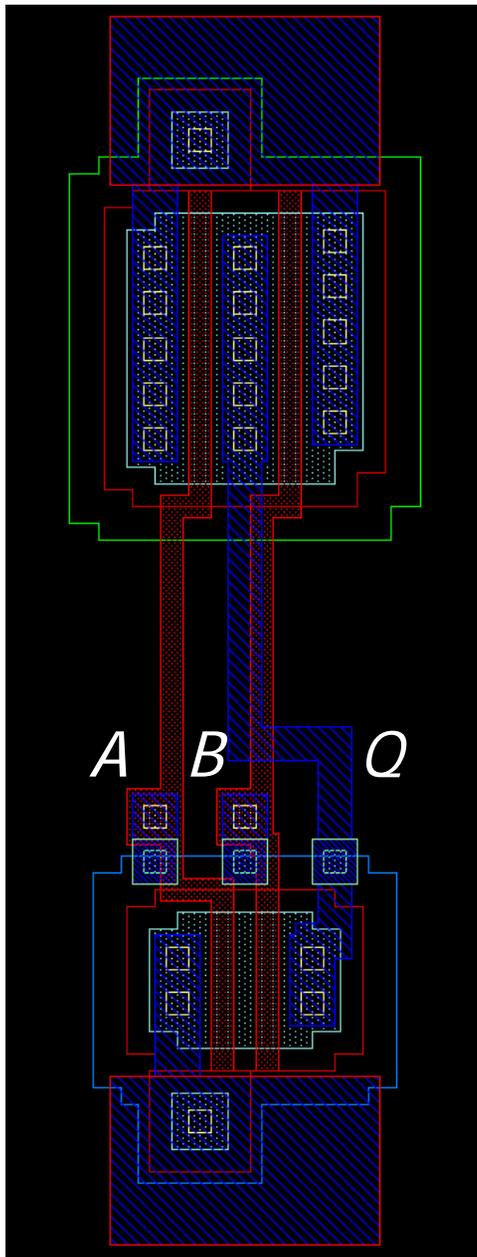
Digital Standard Cells



- ◆ Predefined logic gates (“cells”) - Circuit composed of well-defined, discrete parts connected together
- ◆ write a *description* (program) of the logic functions
- ◆ *synthesize* the design (using the library)
- ◆ *place and route* the design



For example



But This Is Not What We Do



We do mixed-mode design - analog functions, supported by digital logic.

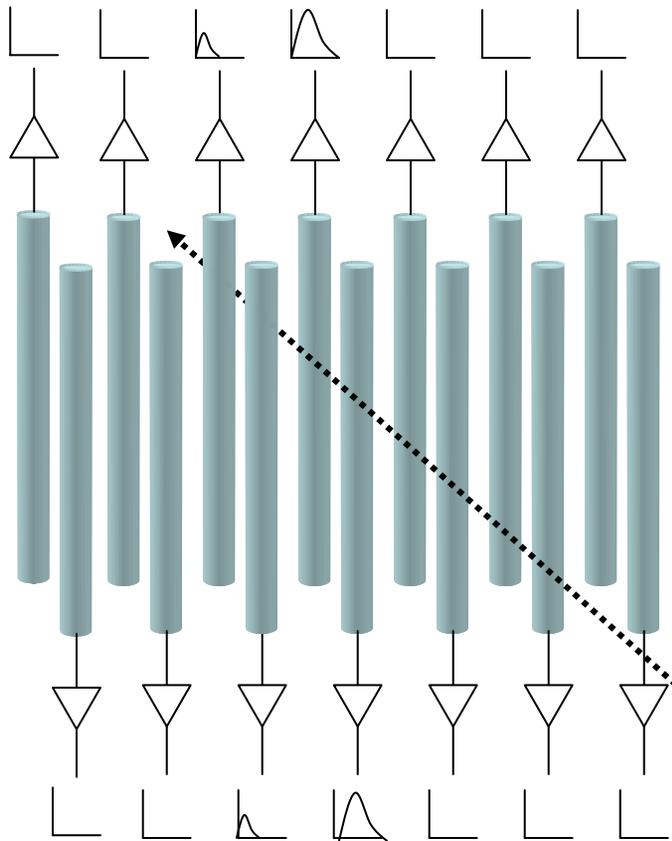
The analog functions are full custom: design the circuit at the transistor level, and design/optimize each transistor for the given function. This is not assembling a collection of pre-defined modules.

Timeout - Glossary

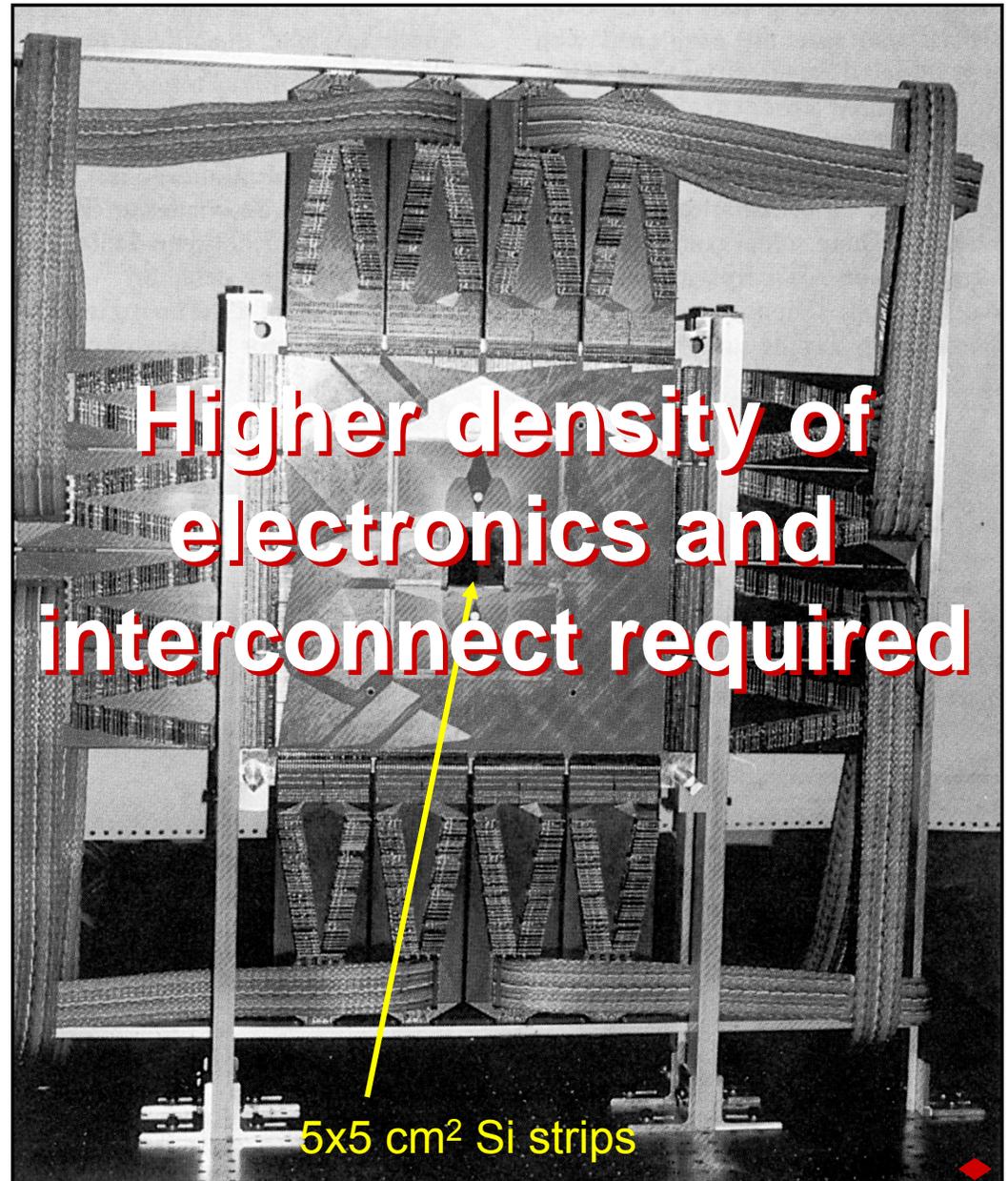
Full custom design means that we draw each transistor. What we can adjust are the width (W) and length (L) of the channel. For a given **process**, the transconductance ($\partial I/\partial V$) and capacitance depend on W, L and the process parameters.

Why do we do this?

Particle Tracking Detectors



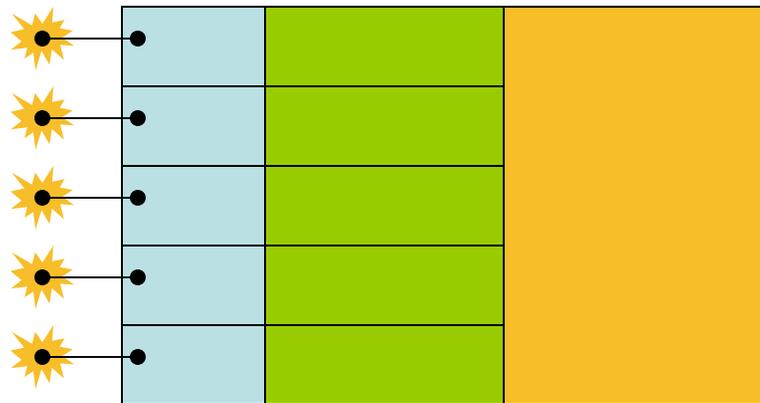
High rate fixed target experiments in the '80s (NA11, E706, ...) needing finer granularity (to reduce occupancy)



What we do



- ◆ Design custom ICs, typically in support of lab programs
- ◆ Generally, these ICs have many channels and are connected to some sort of sensor, transducer, ... at the front-end, do some sort of signal acquisition/processing, and send information, usually digital, off the back end of the chip



Analog FE "Conversion" Digital BE

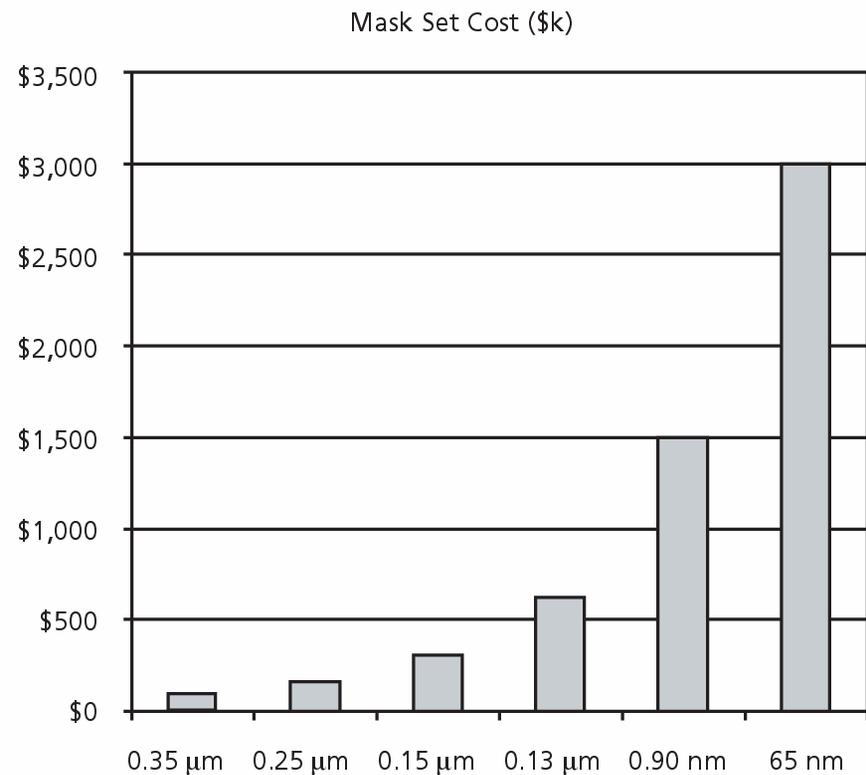
- ◆ We conceptualize the design, implement it electrically and produce the data needed to prepare the masks
- ◆ We *don't* actually fabricate the ICs – we use commercial IC processes



Commercial Processes



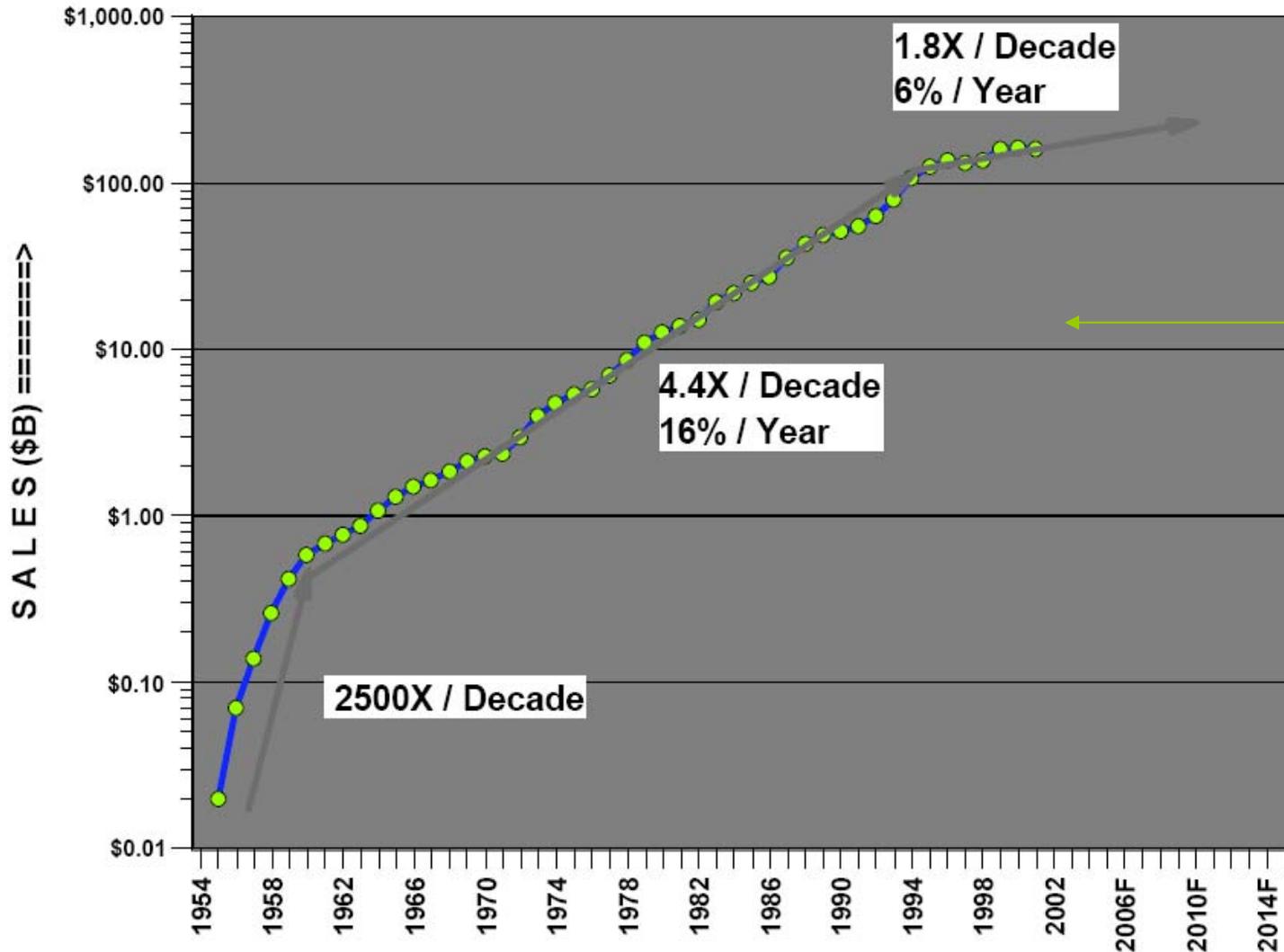
- ◆ Mask sets for modern technologies are very expensive (so we don't work at the cutting edge)
- ◆ One wants to try ideas out first anyway, so we use "Multi-project" services (brokers, who assemble many people's projects onto one run)
- ◆ So our technology choices are limited



Large R&D Investment

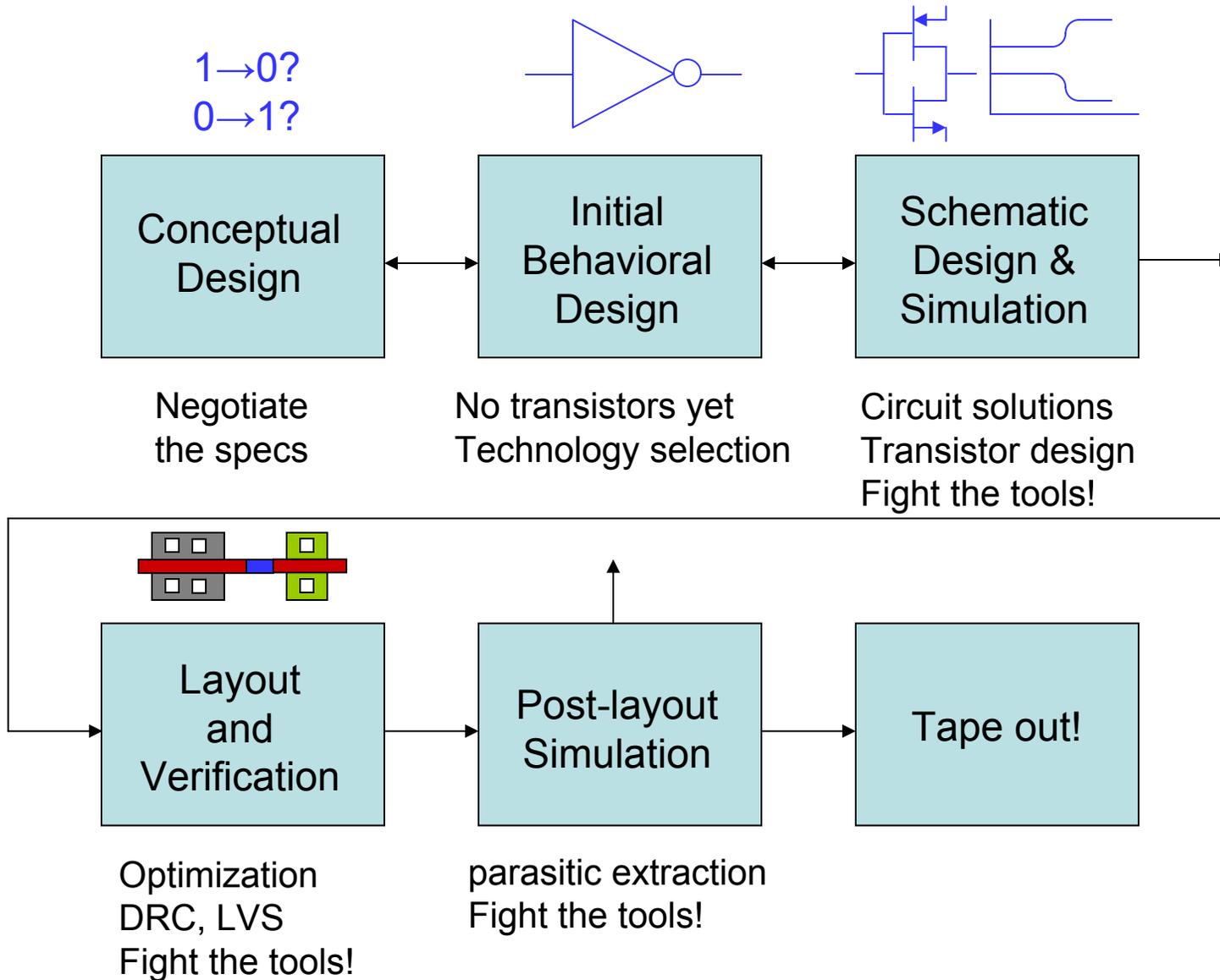


W/W SEMICONDUCTOR INDUSTRY REVENUE (3 Year Avg)



2003 investment
~\$14B (17% of
sales). Recently,
investment ~12-
15% of sales...

Steps in the IC Design Process

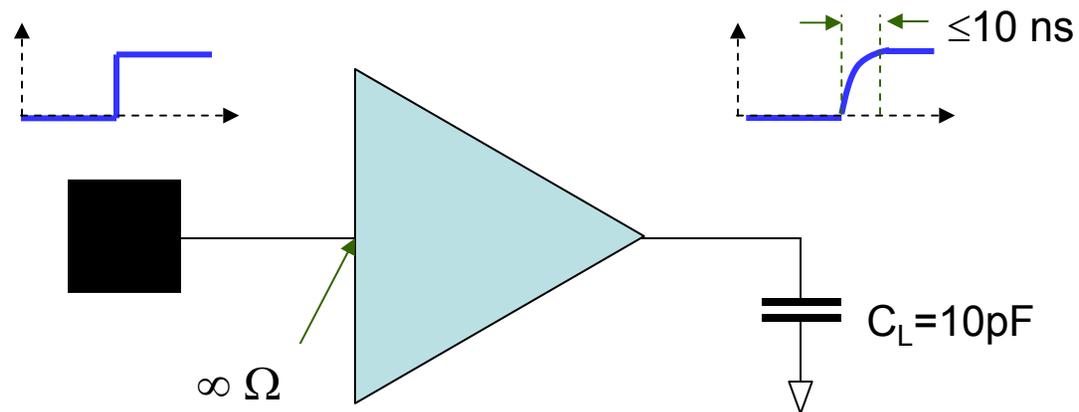


Let's Make A Chip

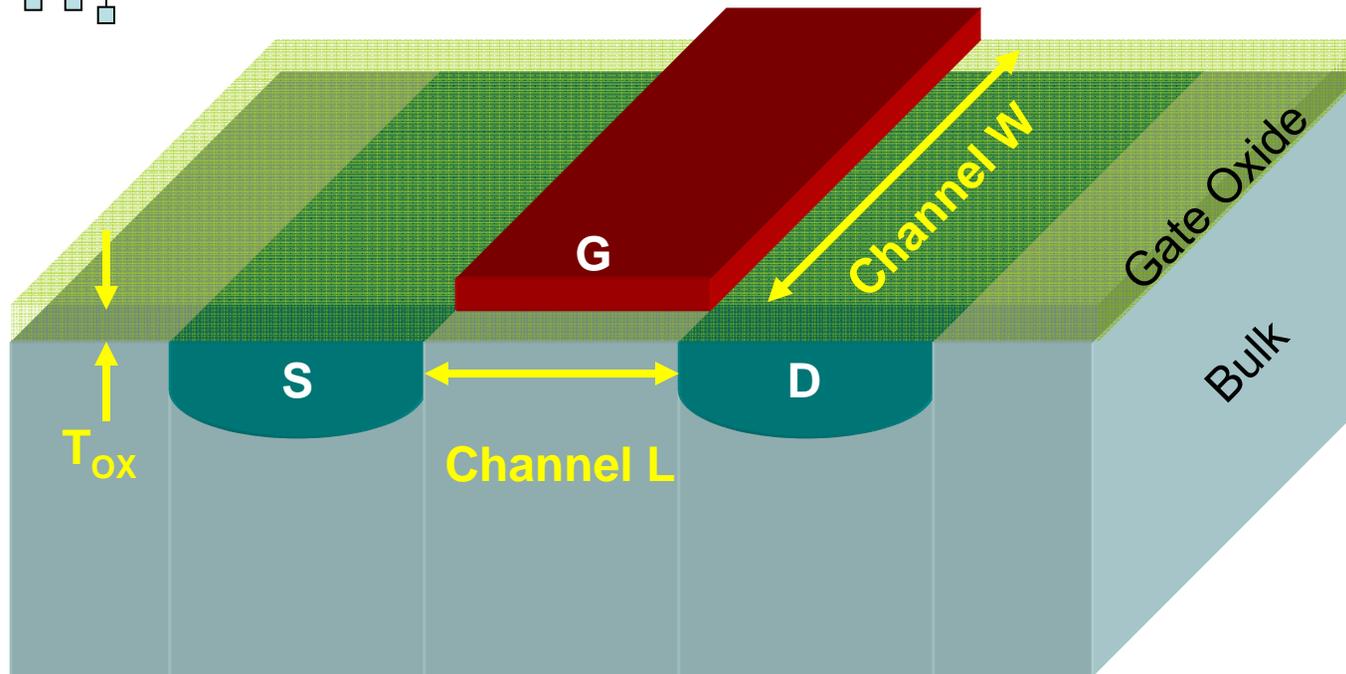
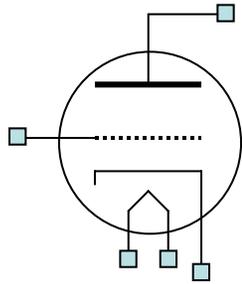


This will be a pretty banal example to fit within the time of this talk

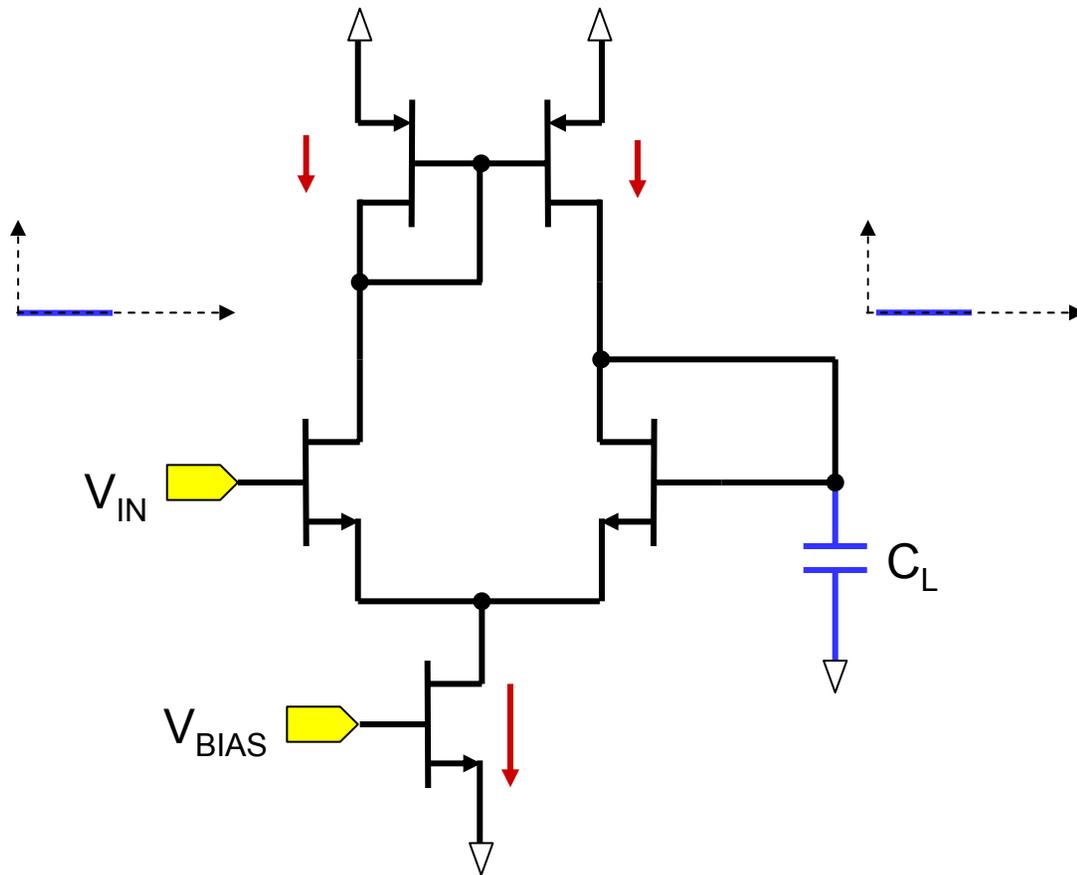
- ◆ For a made-up application, we have a high-output-impedance sensor that needs a buffer amplifier. Specifications:
 - Drive an output load of 1 pF in less than 10 ns
 - Use no more than 1 mW
 - Be precise to >6 bits



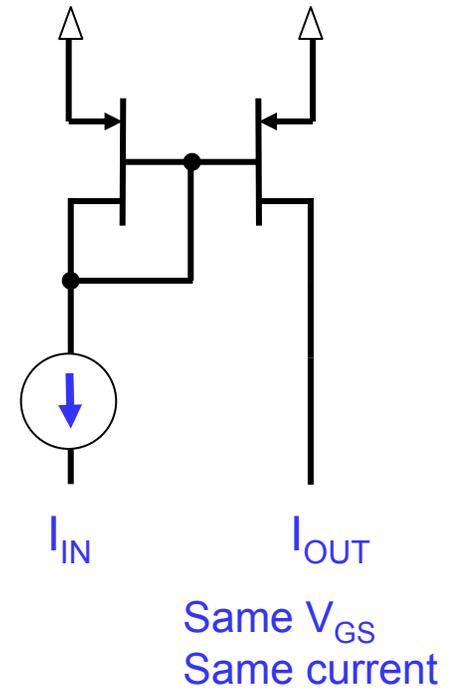
Our Friend the MOS Transistor



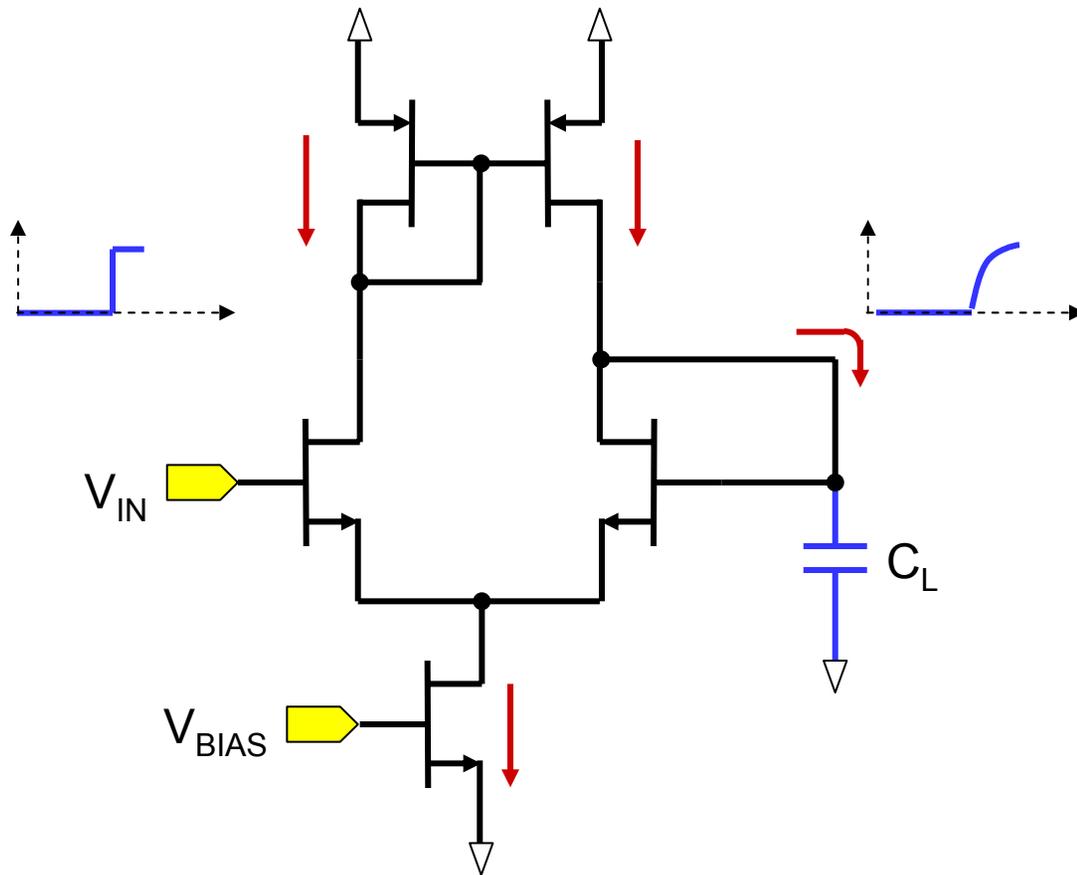
Design



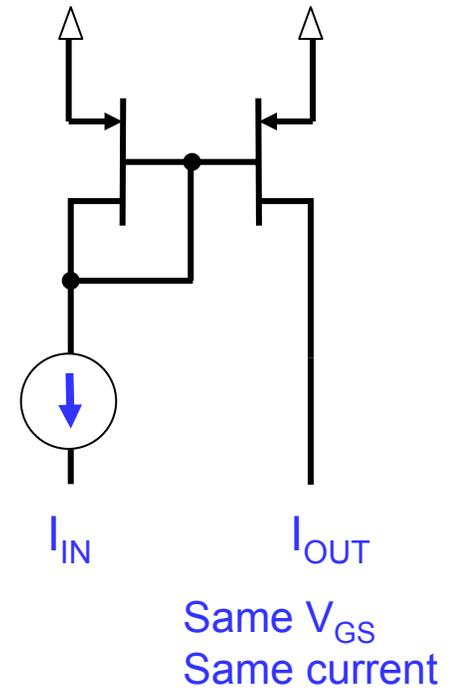
Current Mirror



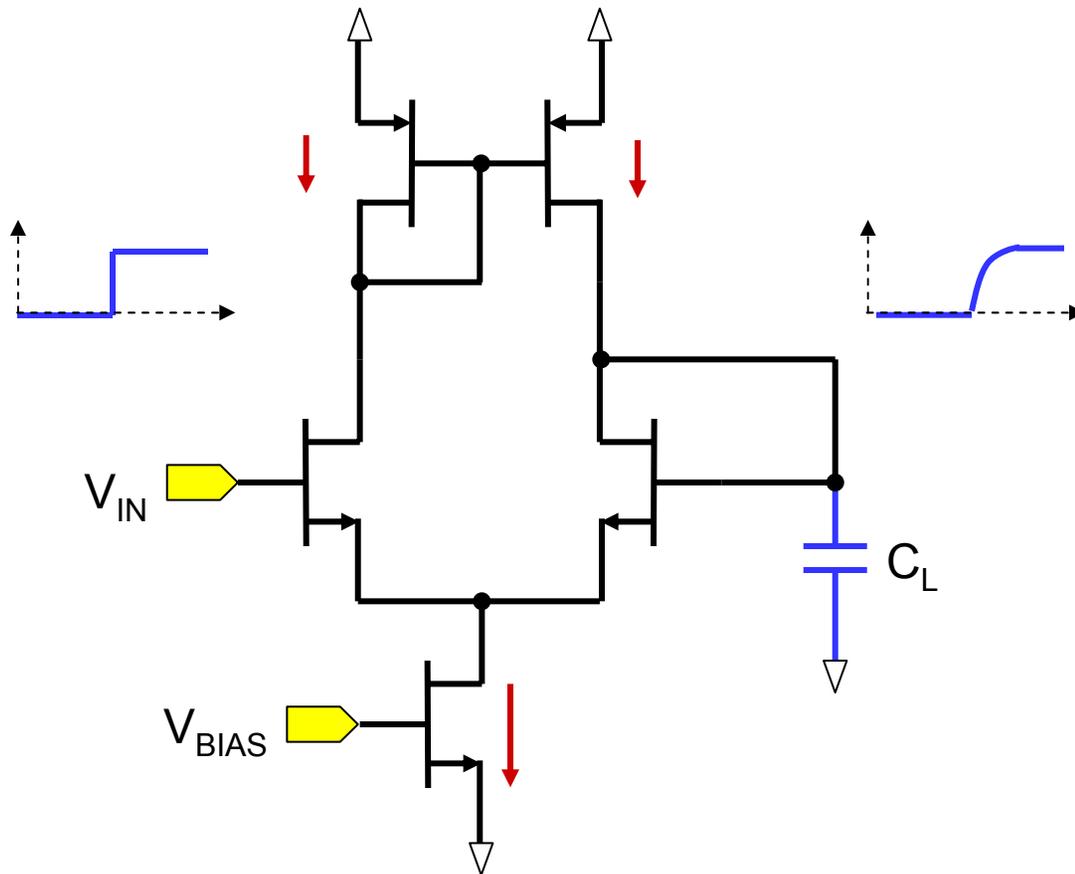
Design



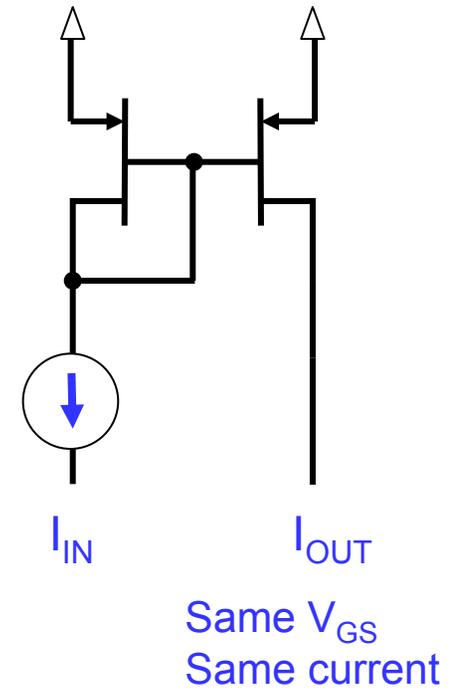
Current Mirror



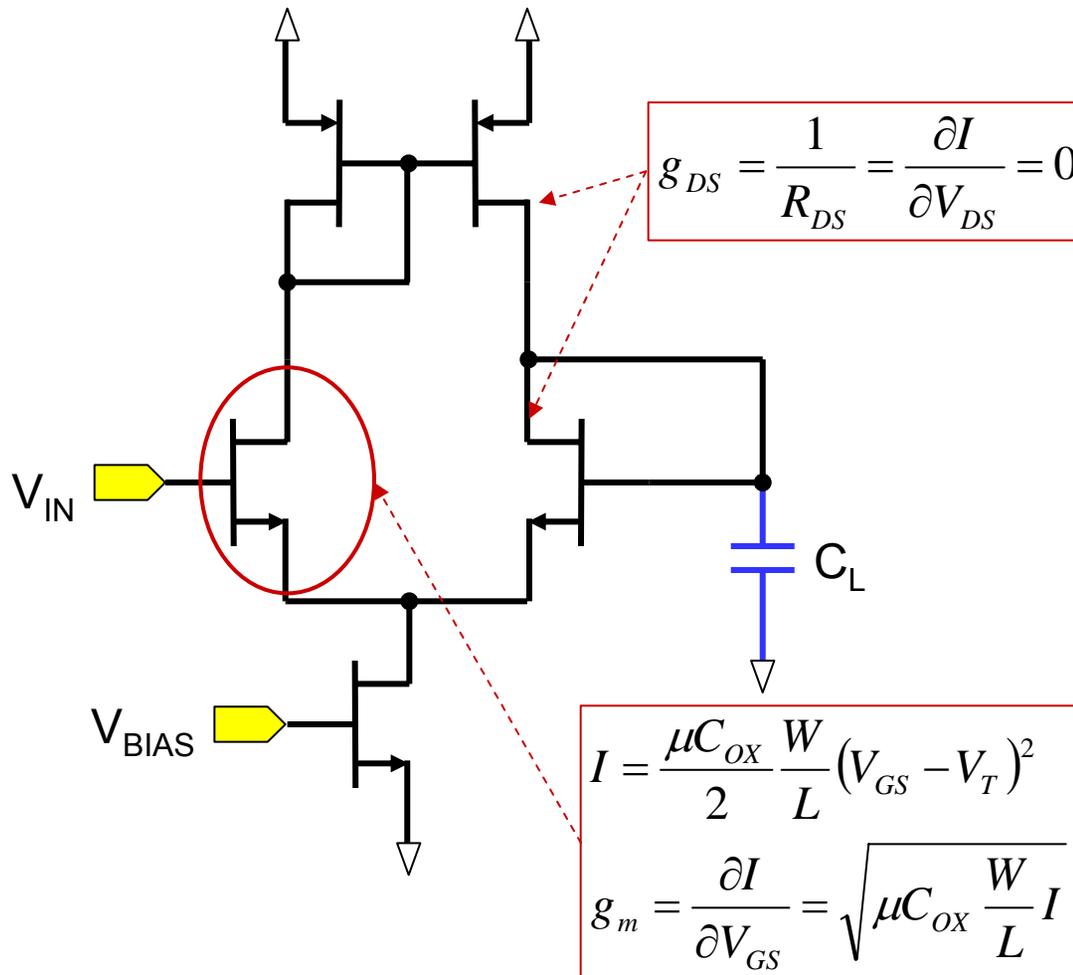
Design



Current Mirror



Hand Calculation



$\mu = 0.03 \text{ m}^2/\text{V}$ **Process**
 $T_{ox} = 7.1 \text{ nm}$ **Parameters**

$$C_{ox} = \frac{\epsilon_{ox} \epsilon_0}{T_{ox}} = 0.0048 \text{ F/m}^2$$

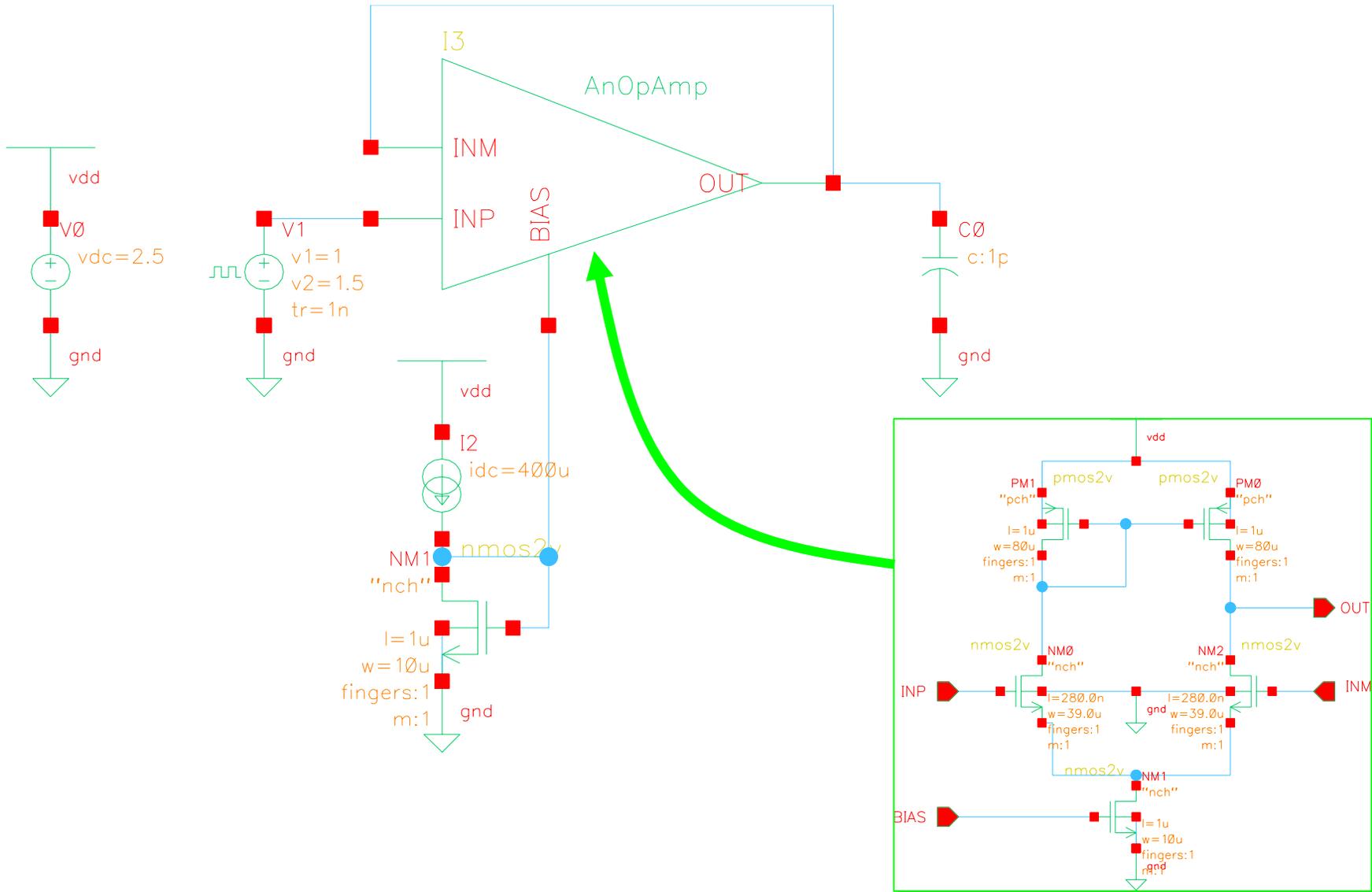
1 mW \Rightarrow 400 μA

$$g_m = \frac{\partial I}{\partial V_{GS}} = \sqrt{\mu C_{ox} \frac{W}{L} I}$$

$$= 2 \text{ mA/V for } \frac{W}{L} \sim 140$$

Check the calculation with simulation

Simulation Schematic



Simulation



Netlist

```
MS2 D1 D1 VDD VDD PCH L=1U W=80U M=1
C1 OUT GROUND 1P
V3 N$617 GROUND DC 0V AC 1 0
V2 INP N$617 PULSE ( 1 1.5 50N 1NS 1NS 1 2 )
I1 VDD N$207 DC 0.25MA
MN4 N$207 N$207 GROUND GROUND NCH L=1U W=20U M=1
MN3 OUT OUT S1 GROUND NCH L=0.28U W=39U M=1
MN2 D1 INP S1 GROUND NCH L=0.28U W=39U M=1
MS1 OUT D1 VDD VDD PCH L=1U W=80U M=1
MN1 S1 N$207 GROUND GROUND NCH L=1U W=20U M=1
V1 VDD GROUND DC 2.5V
```

Choice of model

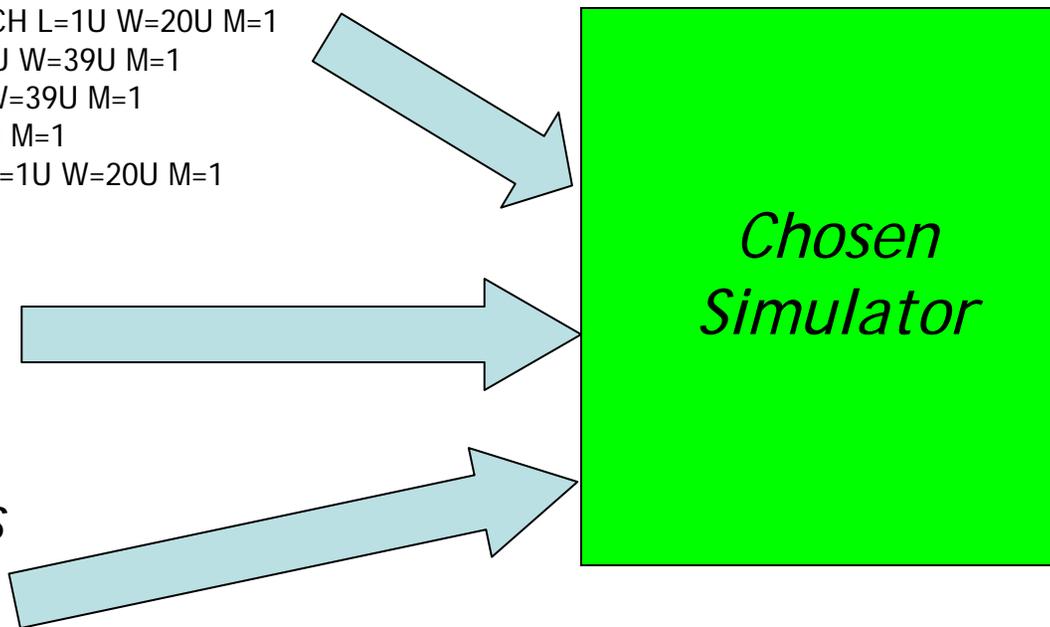
$$I = \frac{\mu C_{ox}}{2} \frac{W}{L} (V_{GS} - V_T)^2$$

Process parameters

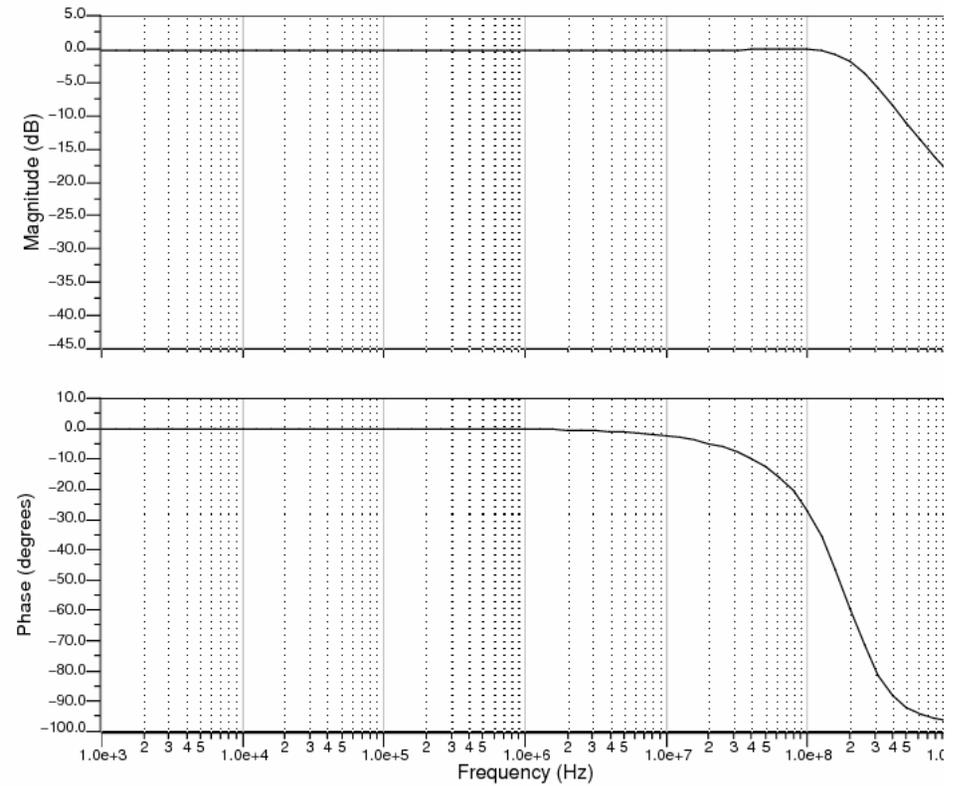
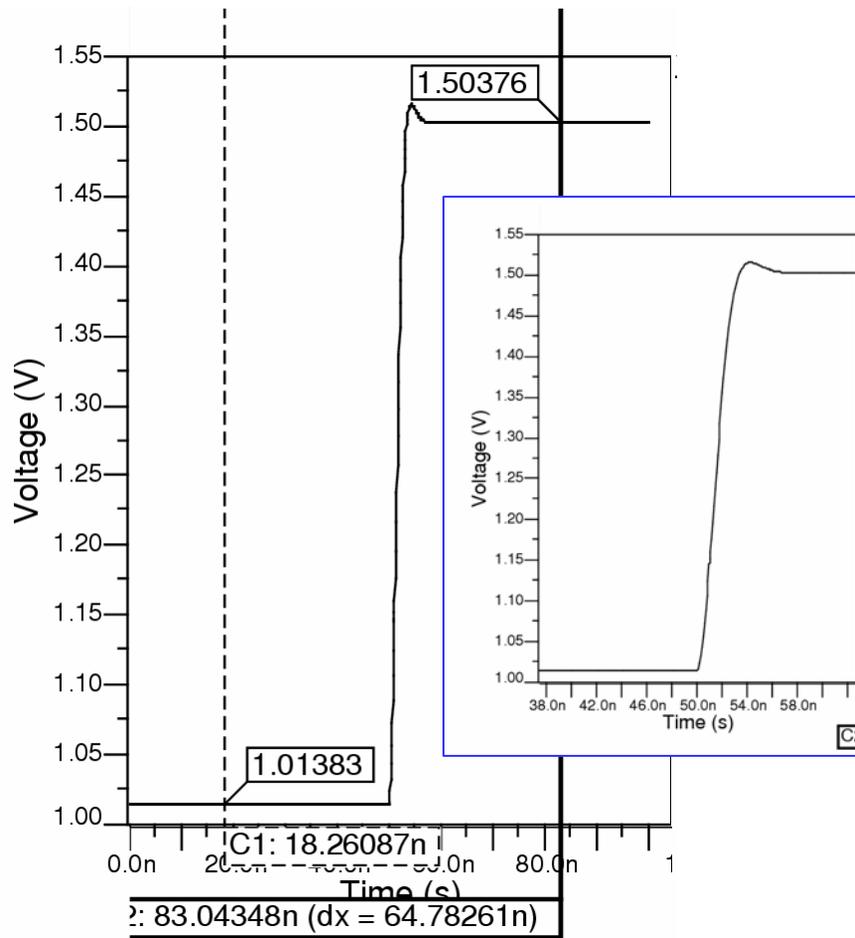
$$\mu = 0.03 \text{ m}^2/\text{V}$$

$$T_{ox} = 7.1 \text{ nm}$$

$$C_{ox} = \frac{\epsilon_{ox} \epsilon_0}{T_{ox}} = 0.0048 \text{ F/m}^2$$



How Did We Do?



Response to a 1 \rightarrow 1.5V step

2nd Order Effects are Critical in IC Design

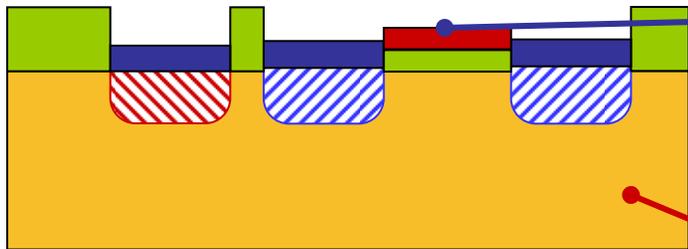


- ◆ g_m – not too bad, hand calculation $\rightarrow 2 \text{ mA/V}$, simulation $\rightarrow 1.86 \text{ mA/V}$
- ◆ R_{DS} – not so good, hand calculation $\rightarrow \infty \Omega$, simulation $\rightarrow 24 \text{ k}\Omega$
 - Channel length modulation: $I_{DS} \rightarrow I_{DS}(1 + \lambda V_{DS})$ so $R = 1/\lambda I_{DS}$
- ◆ DC gain – not so good, hand calculation $\rightarrow \infty$, actual value is $A_V = g_m R_{DS} = 1.86 \text{ mA/V} \times 24 \text{ k}\Omega \sim 50 \Rightarrow$ **offset of 1-2%**
- ◆ OK – so now, I understand everything, right?

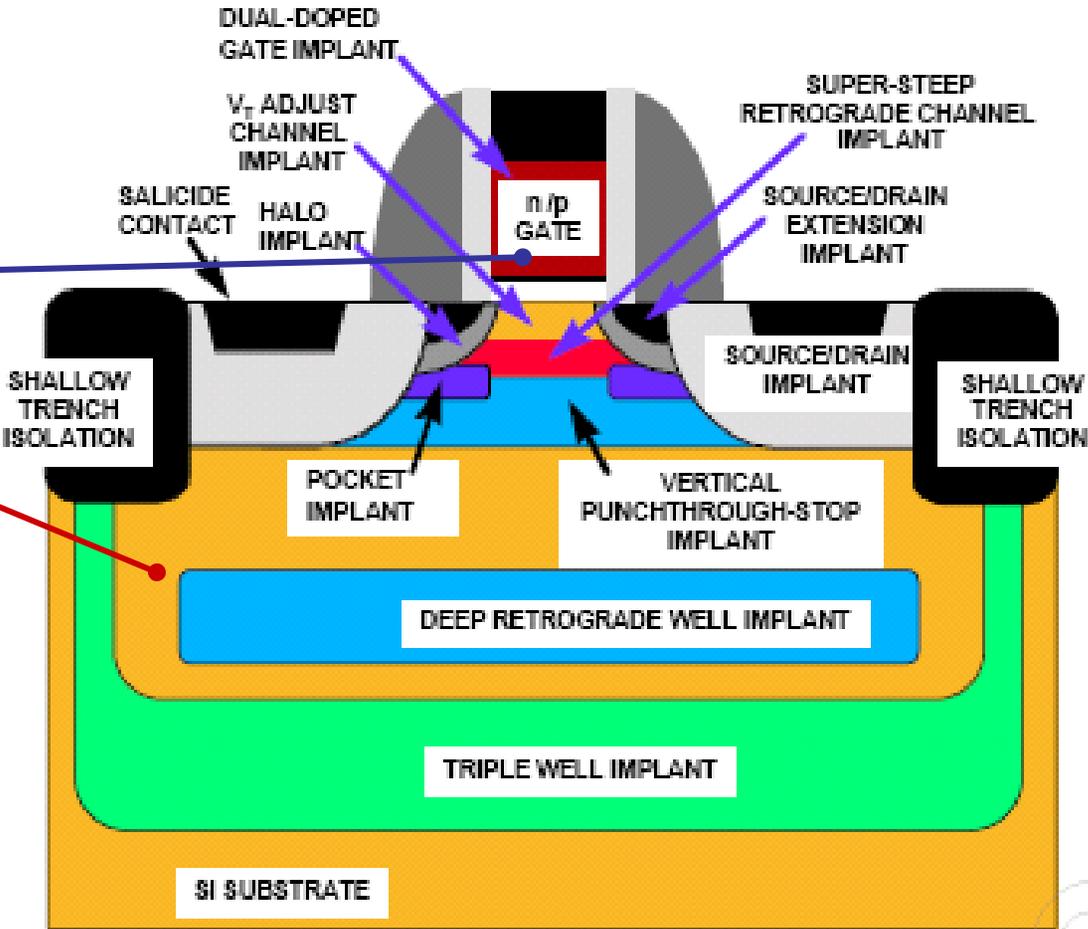
Modern Devices are more Complicated



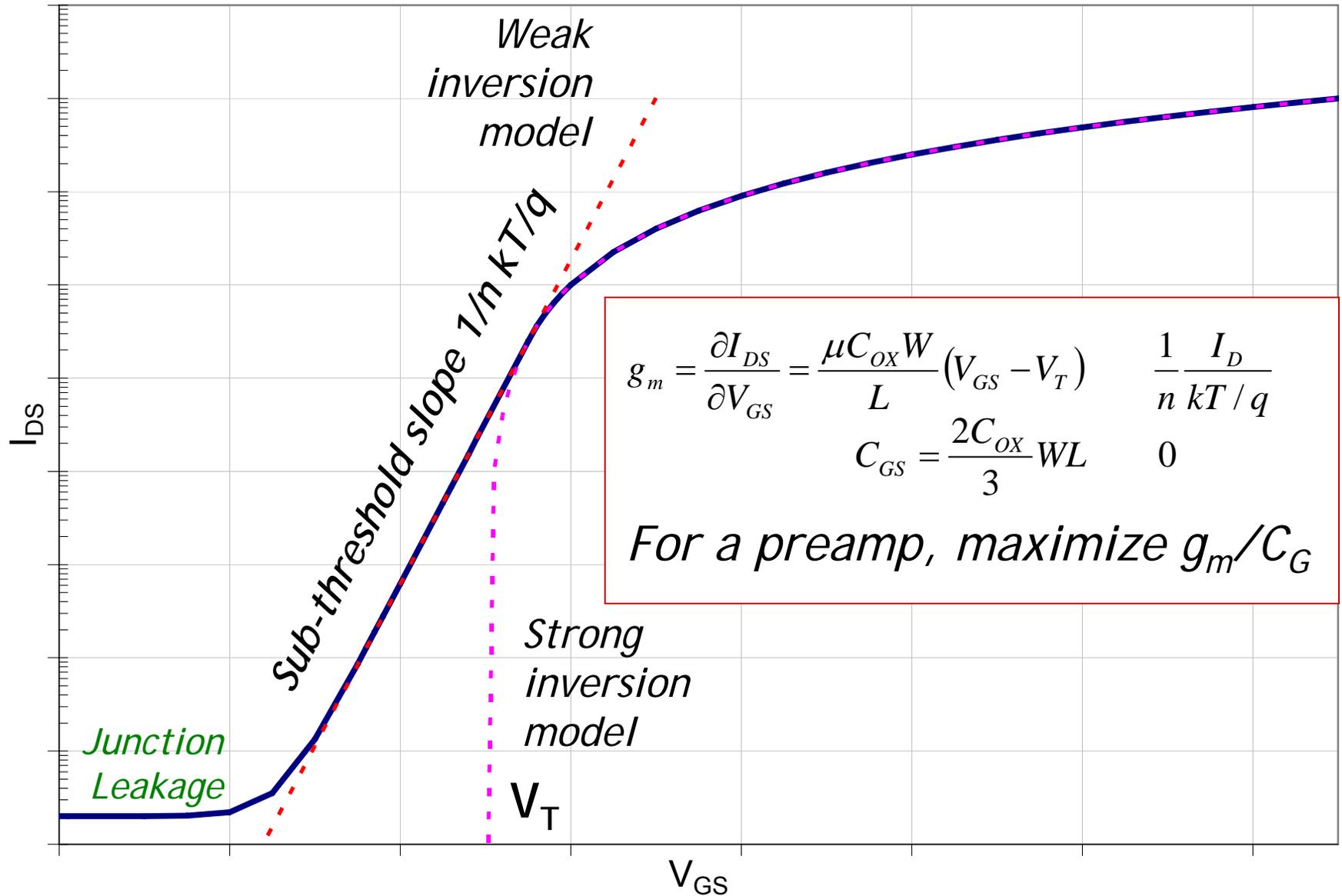
Simple model



Modern Reality



2nd Order Effects may be 1st Order for the Design

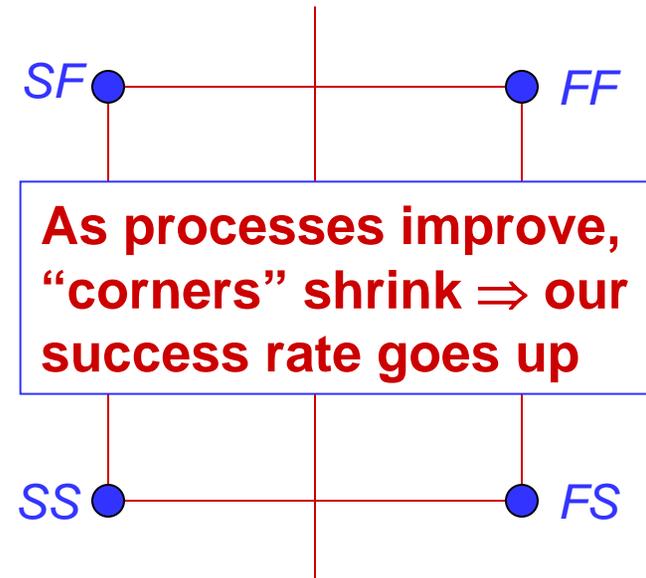


Process Variation



- ◆ Simulation parameters are for the “typical” process
- ◆ But what if you got the “Friday at 4:30” process?
- ◆ Foundries often provide “corner” data which attempt to represent, within device models, what are the “worst” and “best” cases. The designer needs to make sure that the design works under all of these cases (you don’t know who will be running the implanter the day of *your* run)

The process variation models often take the form that one flavor of transistor is “better” (or “faster”) than the other, and the cause may be correlated or anti-correlated with the other flavor. This leads to 5 cases: “typical” and the permutations of the extremes above.



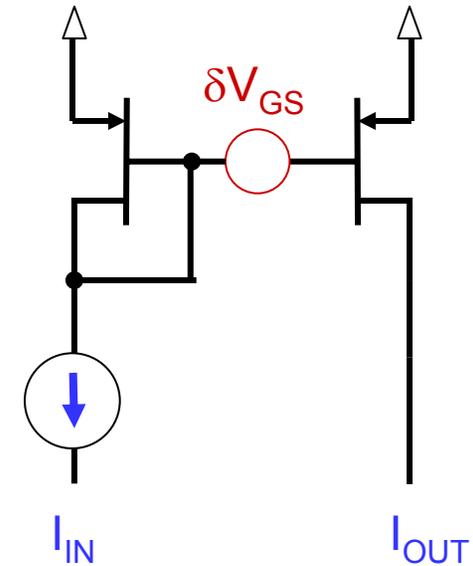
- ◆ OK – so now, I understand everything, right?



Matching

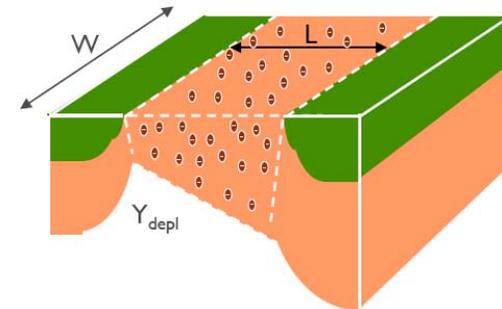


- ◆ Not all Carthusian monks are identical – nor are all MOS transistors
- ◆ Directional variation of implantation across the wafer; statistics of how many dopant atoms there are...



Same V_{GS}
 \neq Same current

PHILIPS example 90 nm CMOS node transistor



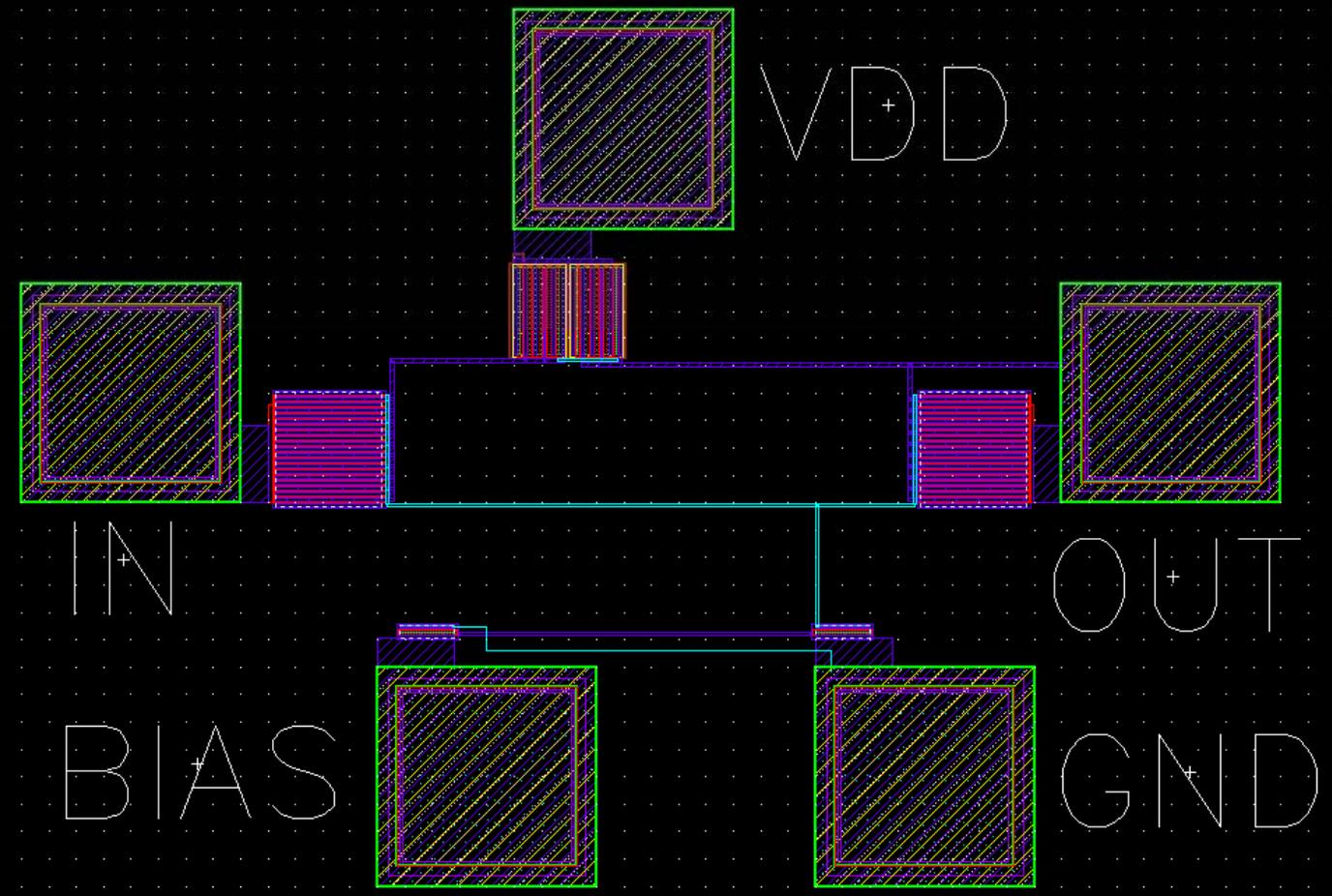
$L \approx 40$ nm (effective)
 $W \approx 60$ nm (effective)
 $Y_{depl} \approx 25$ nm
 $N_a \approx 2 \times 10^{18}$ /cm³

$n_{act} \sim 1300$ atoms
 Poisson statistics
 1σ fluctuation $\sqrt{n_{act}} \sim 40$ atoms

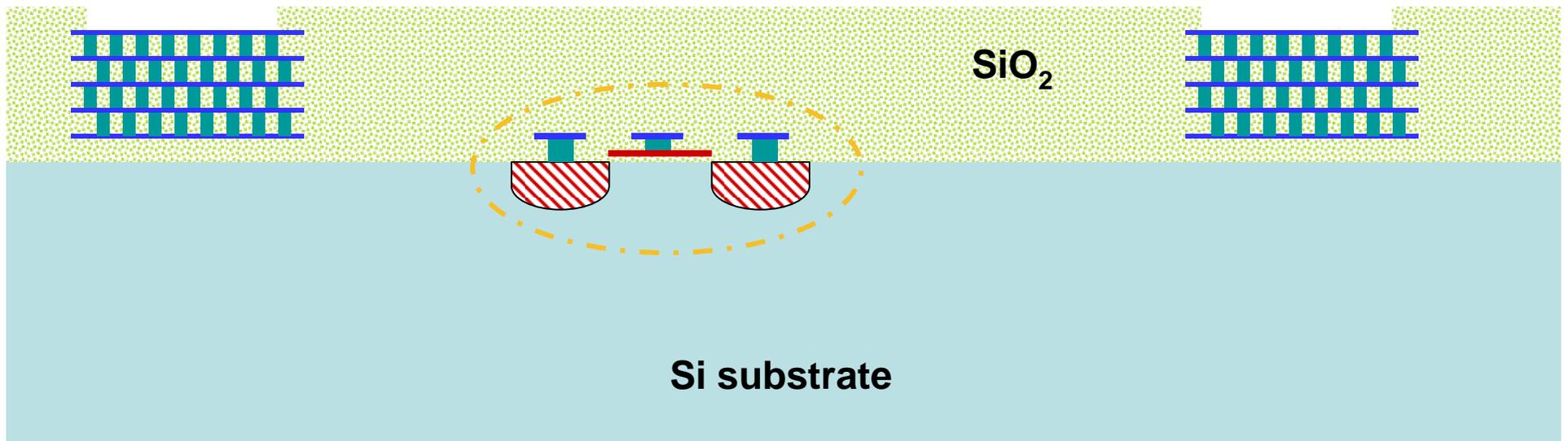
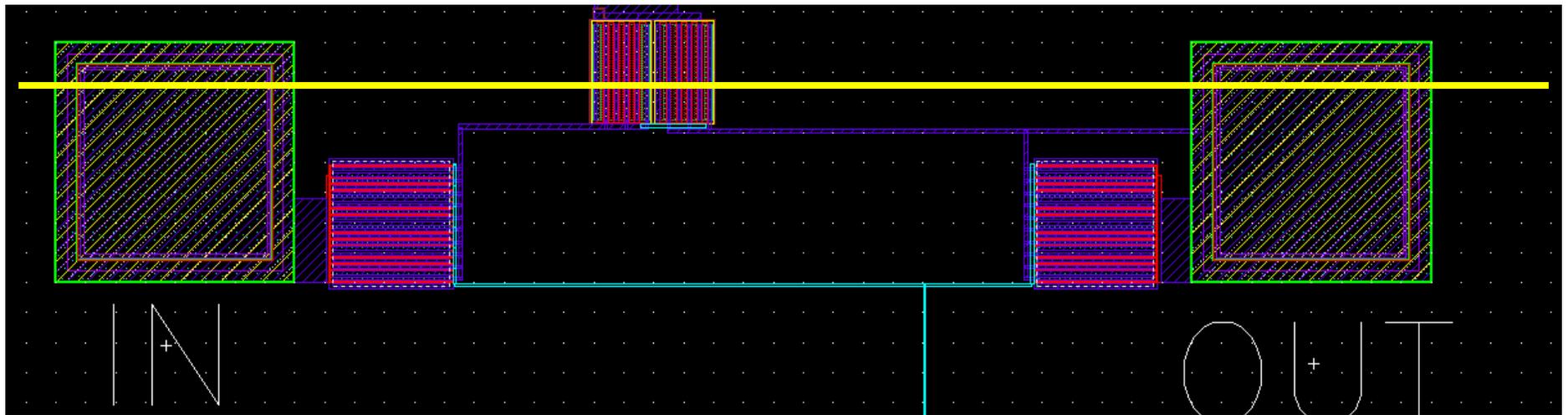


Edit	Help
NWELL	dg
tsmc25rf	
Inst	Pin
AV	NV AS NS
NWELL	dg
DIFF	dg
DIFF	dn
OD2	dg
N3V	dg
PIMP	dg
NIMP	dg
POLY1	dg
POLY1	pn
CONT	dg
METAL1	dg
METAL1	pn
VIA12	dg
METAL2	dg
METAL2	pn
PAD	dg
VTP	dg
VIN	dg
VIDP	dg
VTDN	dg
VIA23	dg
METAL3	dg
METAL3	pn
VIA34	dg
ESD	dg

Up to 33 masks in this process



Drawn Layers



Verification



Virtuoso® Layout Editing: junk AnOpAmp layout

X: 103.62 Y: -77.68 (F) Select: 34 DRD: OFF dX: -20.57 dY: -27.49 Dist: 34.334 Cmd: 3

Calibre - DRC RVE : AnOpAmp.drc.results

File View Highlight Setup Help

53 Errors (in 11 of 330 Checks)

- Cell AnOpAmp - 53 Errors
 - Check PO.R.3.Logic - 1 Error
 - Check M1.S.2 - 1 Error
 - 01
 - Check M1.A.1 - 5 Errors
 - Check M1.R.1 - 1 Error
 - Check M2.R.1 - 1 Error
 - Check M3.R.1 - 1 Error
 - Check M4.R.1 - 1 Error
 - Check LAT.3P - 5 Errors
 - Check LAT.3N - 23 Errors
 - Check_PO.I.1.MM - 13 Errors
 - Check_MST.R.1 - 1 Error

Cell Top

S-Vertex Polygon

Coordinates: (in AnOpAmp)

104.428	-74.1
104.618	-74.16
105.0	-74.497
105.0	-74.28
105.122	-74.28
104.932	-74.22
104.55	-73.883
104.55	-74.1

Checktext

```
M1.S.2 { @ Wide M1 to M1 spacing < 0.60
M1_S5 = SHRINK (SHRINK (SHRINK (SHRINK M1 RIGHT BY 5) LEFT BY 5) TOP BY 5) BOTTOM BY 5
M1_G5 = GROW (GROW (GROW (GROW M1_S5 RIGHT BY 5) LEFT BY 5) TOP BY 5) BOTTOM BY 5
M1_Wide = M1_G5 AND M1
M1_Exp = SIZE M1_Wide BY 1 INSIDE OF M1 STEP 0.223
M1_Branch = M1_Exp NOT M1_Wide
M1_Branch_edge = M1_Branch COIN INSIDE EDGE M1
M1_Check = M1 AND (SIZE M1_Exp BY 0.6)
M1_Else = M1_Check NOT INTERACT M1_Exp
M1_Extend = M1_Check NOT M1_Exp
EXT M1_Wide M1_Else < 0.6 ABUT >0 <89.5 REGION
EXT M1_Branch_edge M1_Else < 0.6 ABUT >0 <89.5 OPPOSITE REGION
EXT M1_Branch_edge M1_Else < 0.6 ABUT >0 <89.5 CORNER REGION
EXT M1_Branch_edge M1_Else < 0.6 ABUT >0 <89.5 PROJ=0 REGION
A = EXT M1_Exp < 0.6 ABUT >0 < 89.5 SPACE REGION
A NOT INTERACT M1_Extend
}
```

Cell AnOpAmp [Check M1.S.2] : 1 of 1 Error

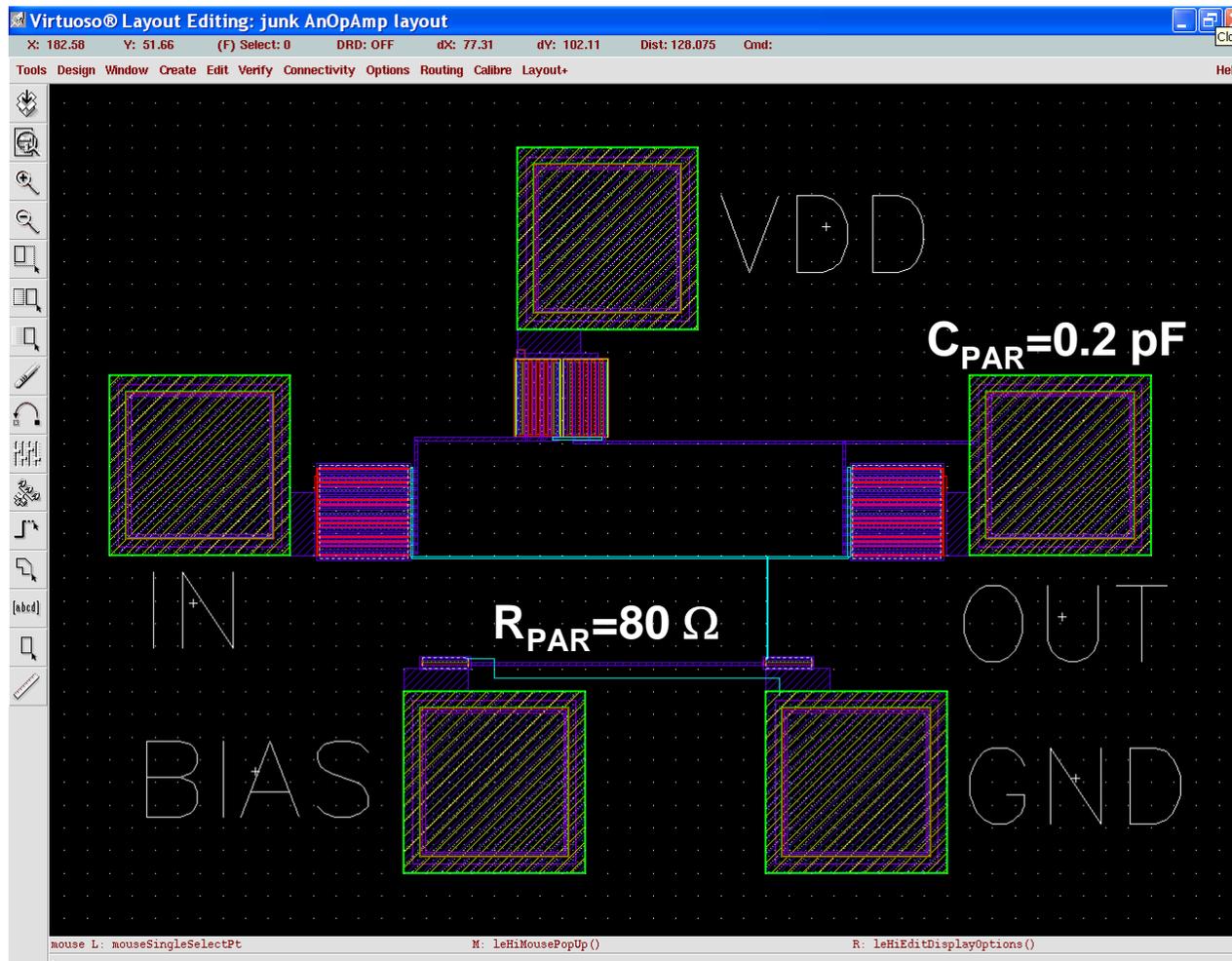
mouse L: mouseSingleSelectPt M: leHiMousePopUp() R: geScroll(nil "w" nil)

- DRC
- LVS

Still Not Done



- ◆ Extraction (of parasitics) and “post-layout” simulation
- ◆ 2nd Order Effects are Critical in IC Design



Various other design sins not checked

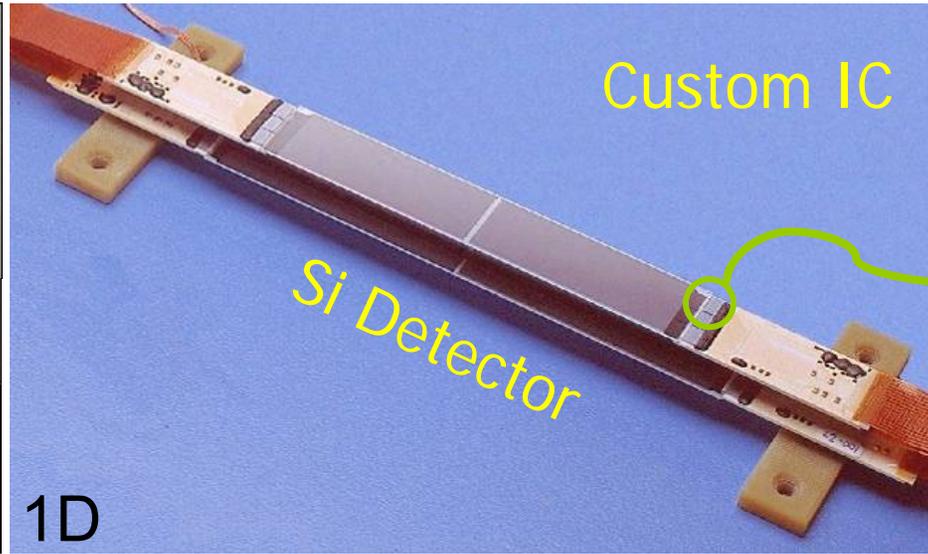
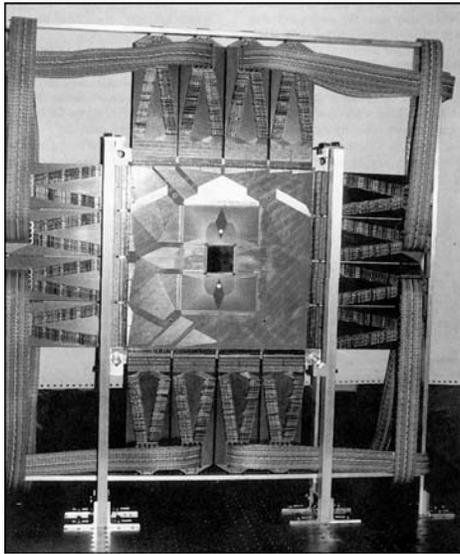


Current IC Group Projects

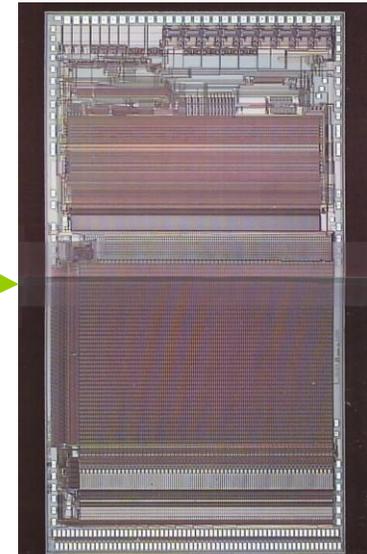


- ◆ 4-channel CCD readout (CDS + 16 bit dynamic range digitizer) for SNAP (space qualified)
- ◆ A “high-voltage” clock driver and sequencer for the above (space qualified)
- ◆ A 16-channel higher-speed variant for almost Column-Parallel CCD readout (>100 fps / Megapixel; ≥ 14 bits)
- ◆ 4-channel, 10 GS/s switched capacitor array with digitizers and digital waveform accumulators
- ◆ 16x16-channel CdTe pixel readout for high-energy x-ray astronomy (space qualified)
- ◆ Monolithic detectors (see below)

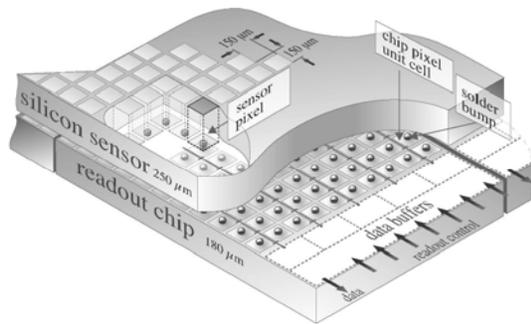
Increasing Integration



1D



2D-Hybrid

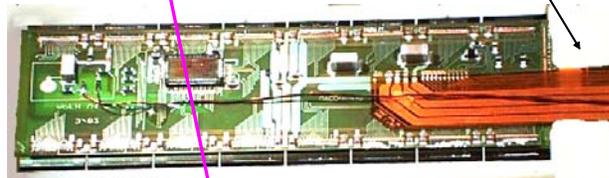


Pixel 2002 - Carmel

Pixel Module

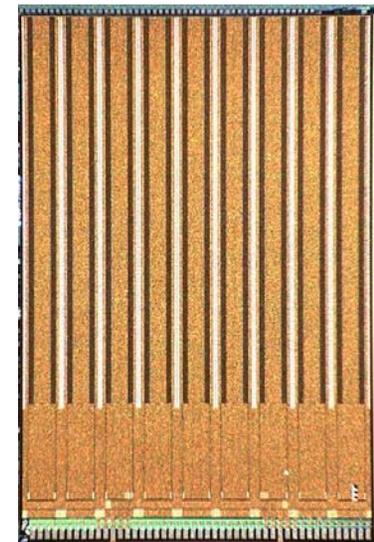
- Sensor
- ASICs
- Flex Hybrid (green)
- Bumps
- ⌒ Wirebonds

Schematic Cross Section (through here)



Pigtail (beyond)

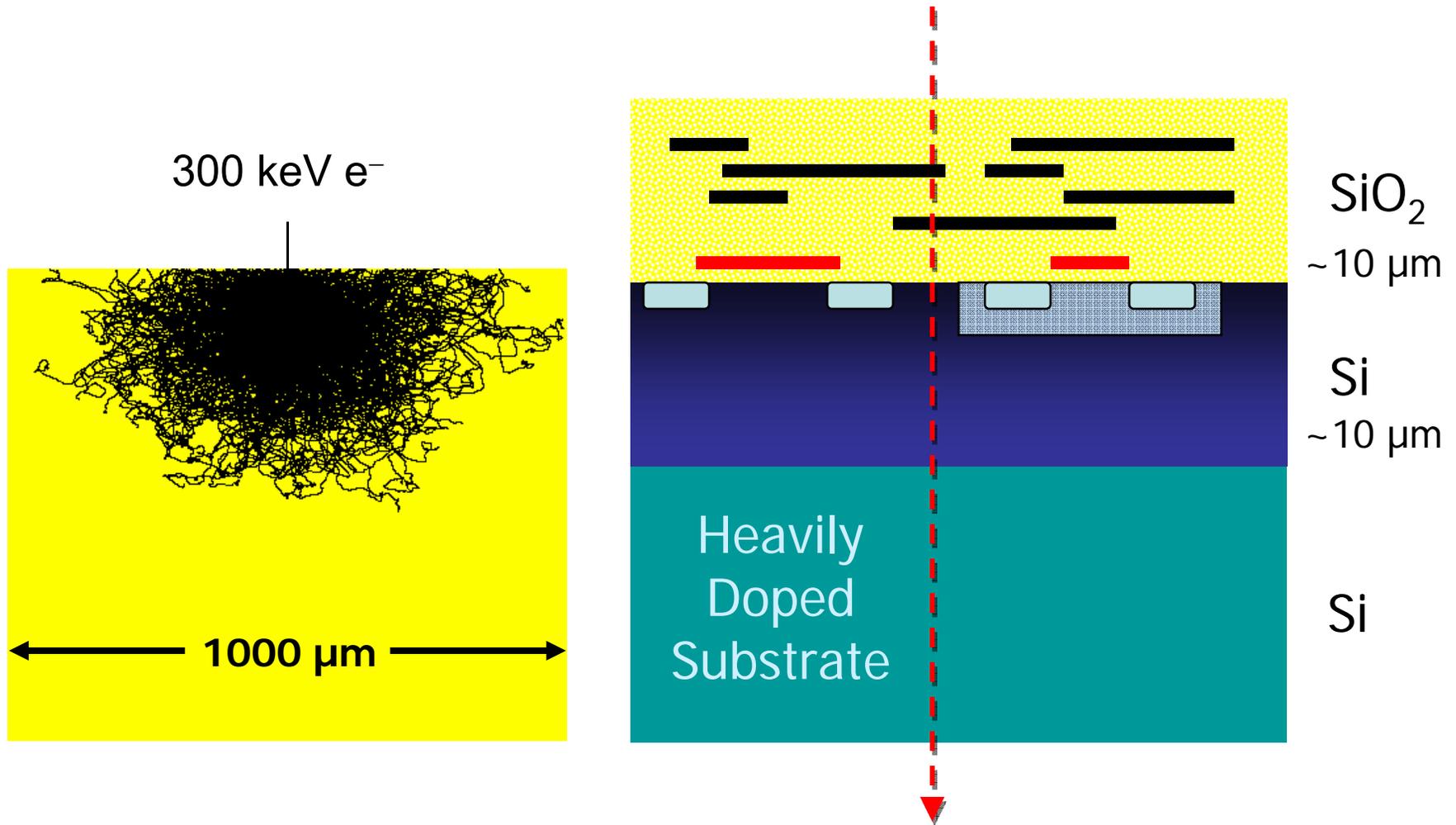
Sept. 9, 2002 M. Garcia-Sciveres - The ATLAS Pixel Detector 14



Active Pixels – the IC is the Detector



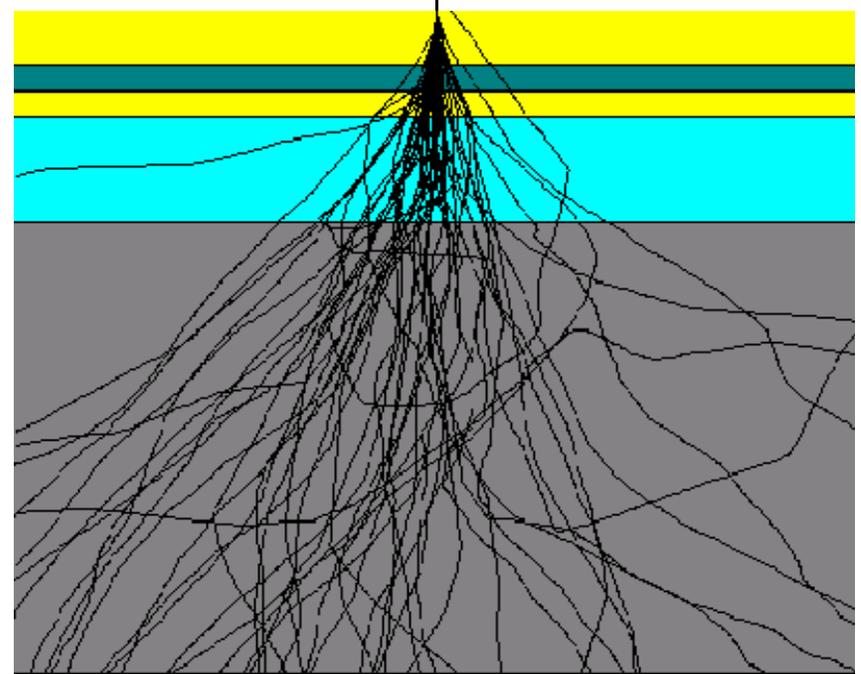
Used to replace CCDs in cheap (and now not-so-cheap) digital cameras
Also might make the ideal detectors for certain types of electron microscopy



Well Adapted to High Sensitivity (speed)



300 keV e⁻



4 μm SiO₂
2 μm Al
2 μm SiO₂
8 μm active Si

Inactive Si

50 μm total

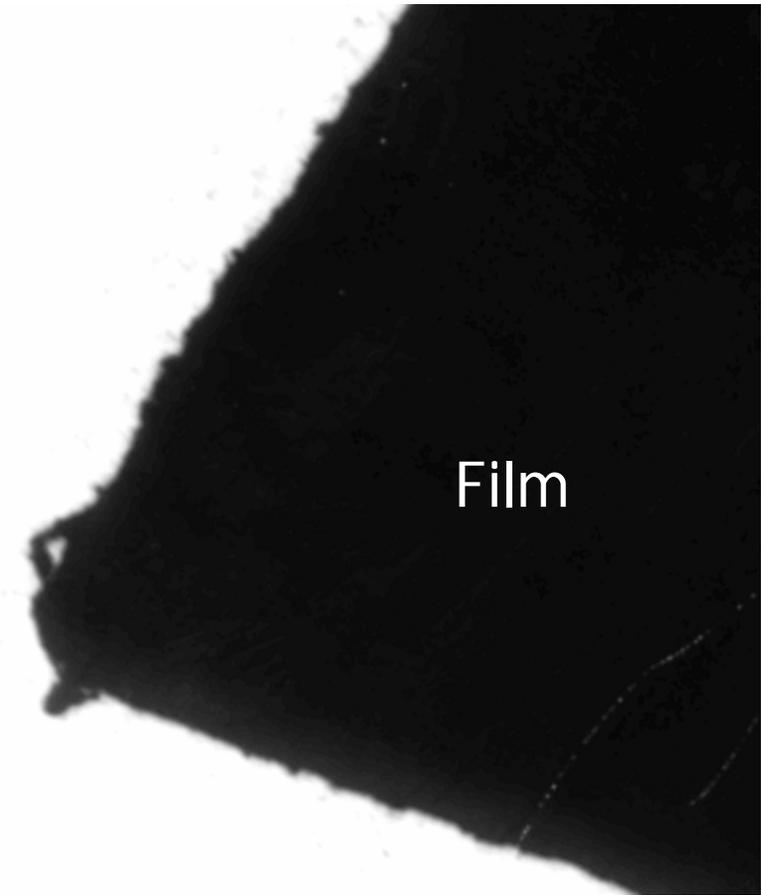
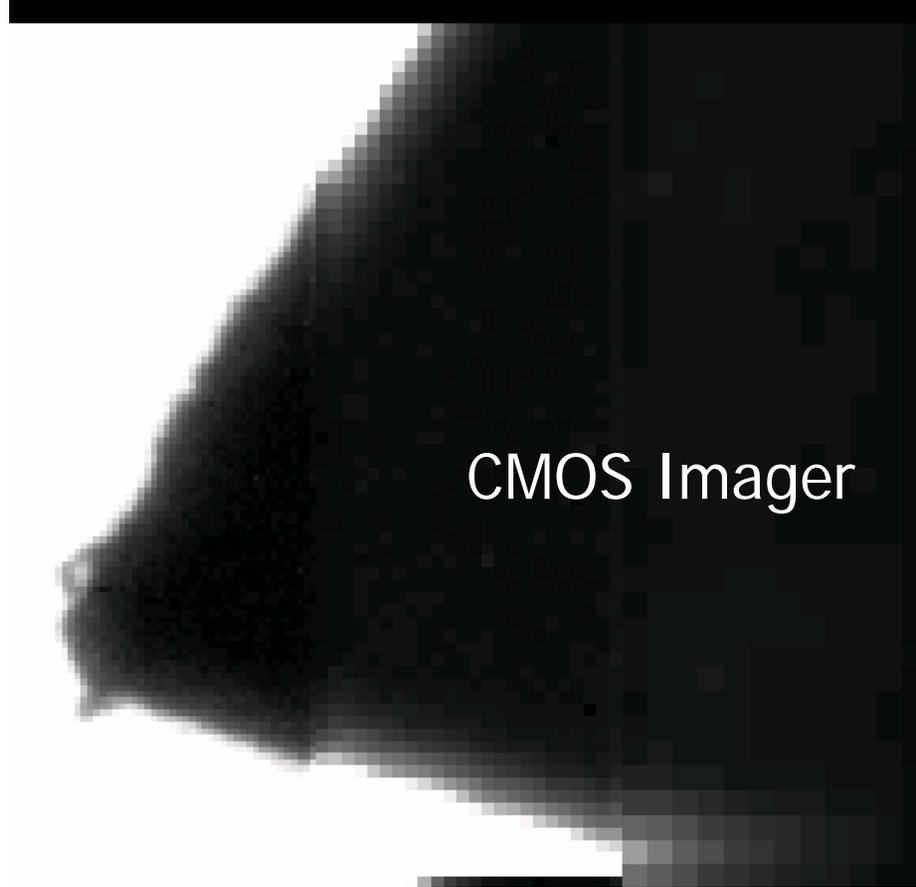
- ◆ Thin detector
- ◆ Thin collection region *within* thin detector
- ◆ Gain – e⁻ are several times minimum ionizing: very high S/N
- ◆ Monolithic – can add on-chip electronics (ADCs, fast readout ...)
- ◆ Use radiation-hardening techniques developed for HEP

← 40 μm →

1st Image (200 keV)



PedFile=_Peds.sum SigFile=_BeamStop.sum Vmax=0.153 Vmin=0.0



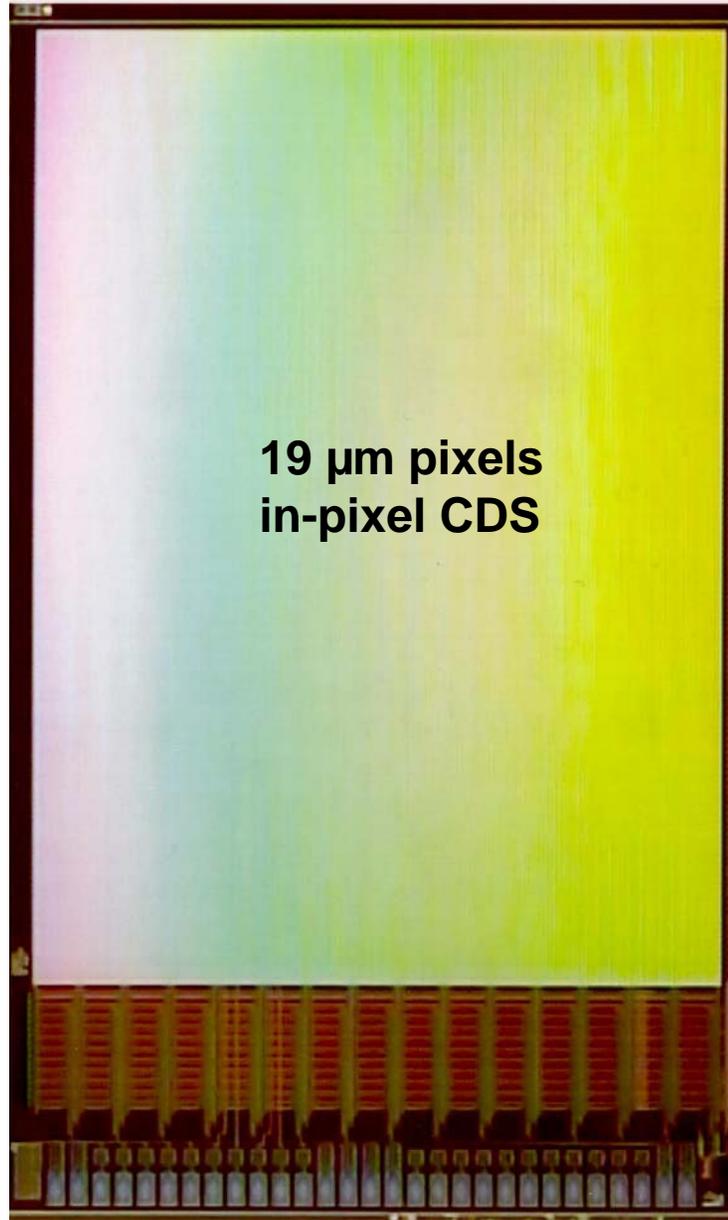
48x144
10 μm Pixels

24x72
20 μm Pixels

12x36
40 μm Pixels

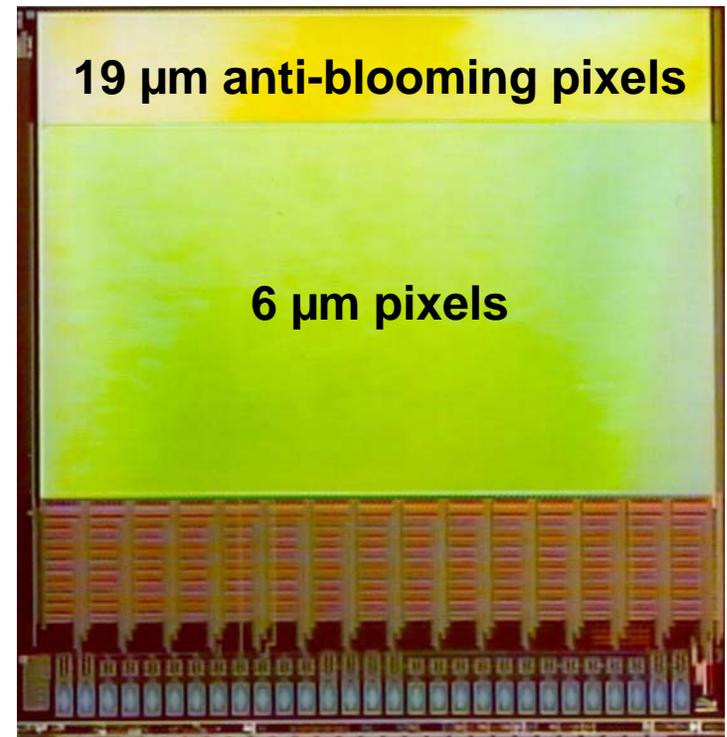
← *Beam stop on the 200 CX at NCEM*

1st Useful Detector Prototypes



**19 μm pixels
in-pixel CDS**

Constructing readout and
user interface software now



19 μm anti-blooming pixels

6 μm pixels

10 bit ADCs
on 19 μm
pitch

Future for IC Design



The experts look ahead

Cramming more components onto integrated circuits

With unit cost falling as the number of components per circuit rises, by 1975 economics may dictate squeezing as many as 65,000 components on a single silicon chip

By Gordon E. Moore

Director, Research and Development Laboratories, Fairchild Semiconductor division of Fairchild Camera and Instrument Corp.

The future of integrated electronics is the future of electronics itself. The advantages of integration will bring about a proliferation of electronics, pushing this science into many new areas.

Integrated circuits will lead to such wonders as home computers—or at least terminals connected to a central computer—automatic controls for automobiles, and personal portable communications equipment. The electronic wrist-watch needs only a display to be feasible today.

But the biggest potential lies in the production of large systems. In telephone communications, integrated circuits in digital filters will separate channels on multiplex equipment. Integrated circuits will also switch telephone circuits and perform data processing.

Computers will be more powerful, and will be organized in completely different ways. For example, memories built of integrated electronics may be distributed throughout the

machine instead of being concentrated in a central unit. In addition, the improved reliability made possible by integrated circuits will allow the construction of larger processing units. Machines similar to those in existence today will be built at lower costs and with faster turn-around.

Present and future

By integrated electronics, I mean all the various technologies which are referred to as microelectronics today as well as any additional ones that result in electronics functions supplied to the user as irreducible units. These technologies were first investigated in the late 1950's. The object was to miniaturize electronics equipment to include increasingly complex electronic functions in limited space with minimum weight. Several approaches evolved, including microassembly techniques for individual components, thin-film structures and semiconductor integrated circuits.

Each approach evolved rapidly and converged so that each borrowed techniques from another. Many researchers believe the way of the future to be a combination of the various approaches.

The advocates of semiconductor integrated circuitry are already using the improved characteristics of thin-film resistors by applying such films directly to an active semiconductor substrate. Those advocating a technology based upon films are developing sophisticated techniques for the attachment of active semiconductor devices to the passive film arrays.

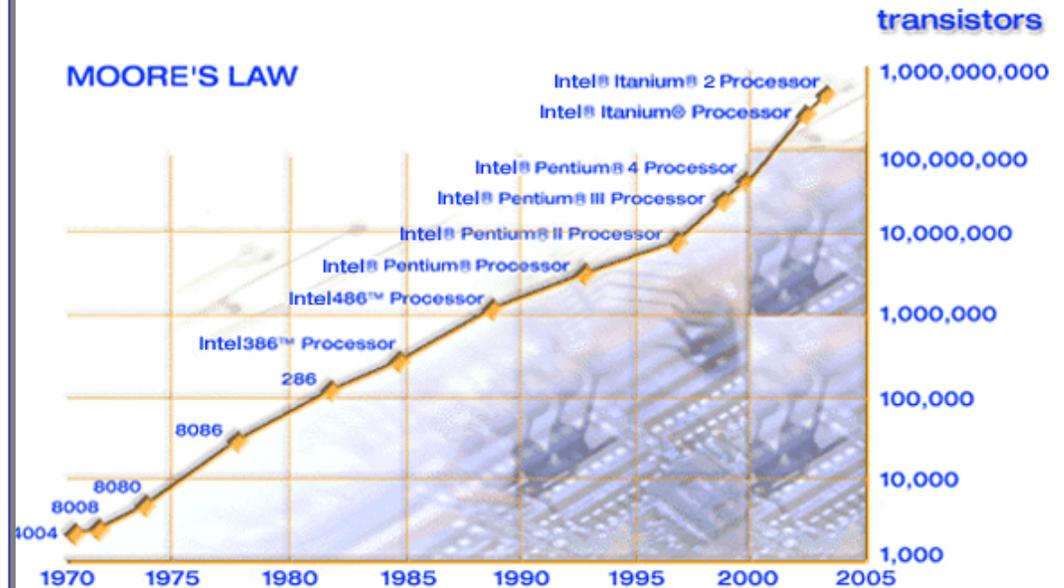
Both approaches have worked well and are being used in equipment today.

The author

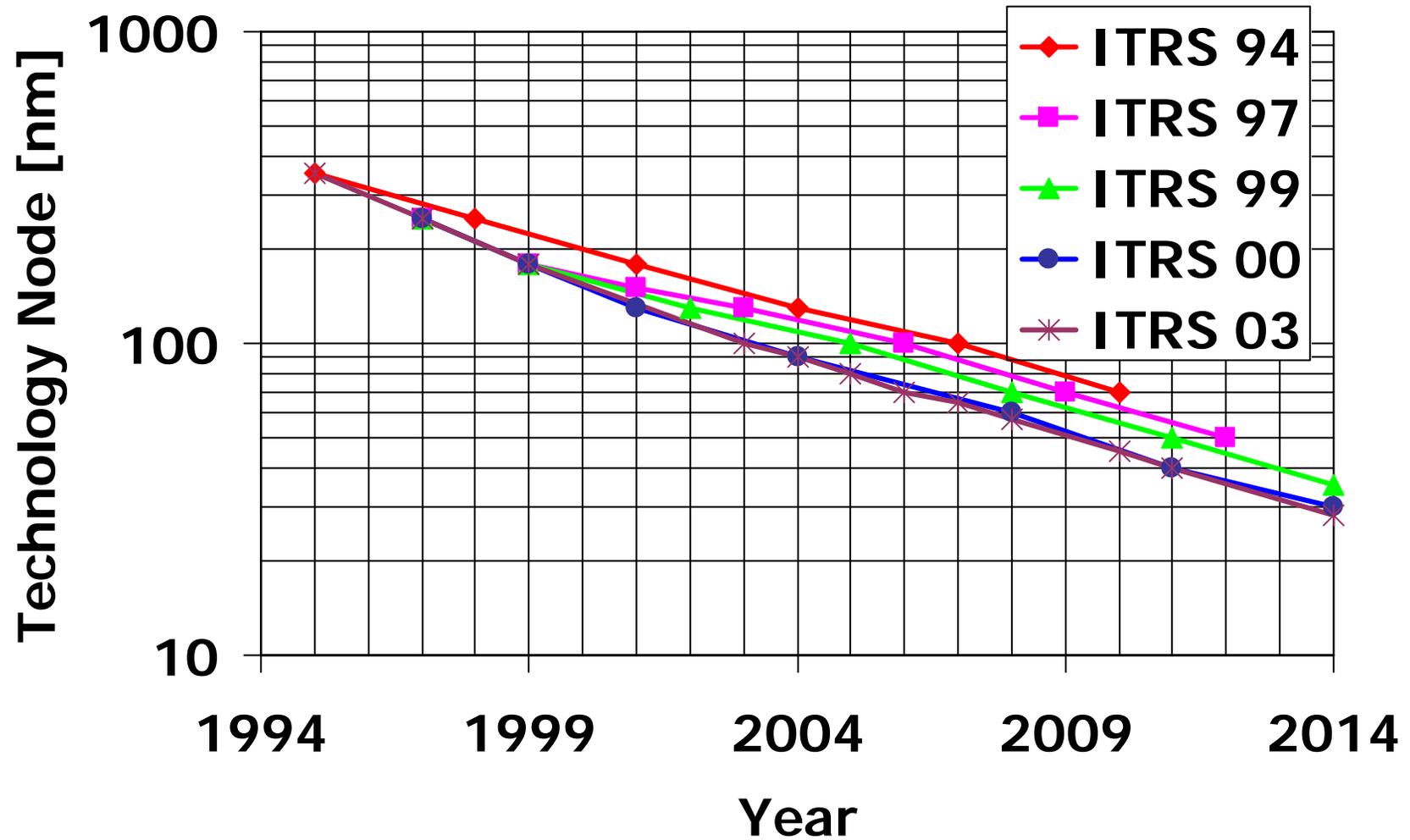
Dr. Gordon E. Moore is one of the new breed of electronic engineers, schooled in the physical sciences rather than in electronics. He earned a B.S. degree in chemistry from the University of California and a Ph.D. degree in physical chemistry from the California Institute of Technology. He was one of the founders of Fairchild Semiconductor and has been director of the research and development laboratories since 1959.

Electronics, Volume 38, Number 8, April 19, 1965

Mandatory Plot



Technology Node Scaling



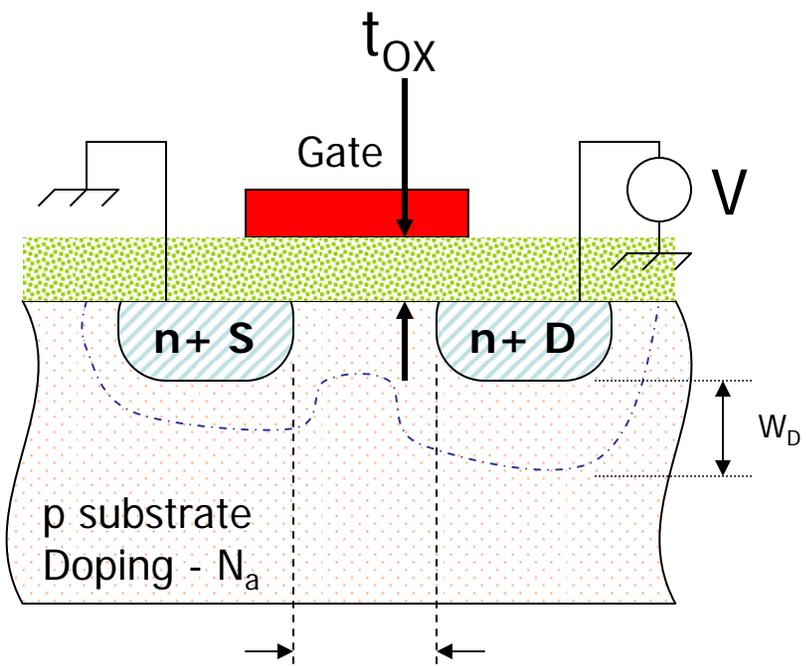
International Technology Roadmap for Semiconductors



CMOS Scaling

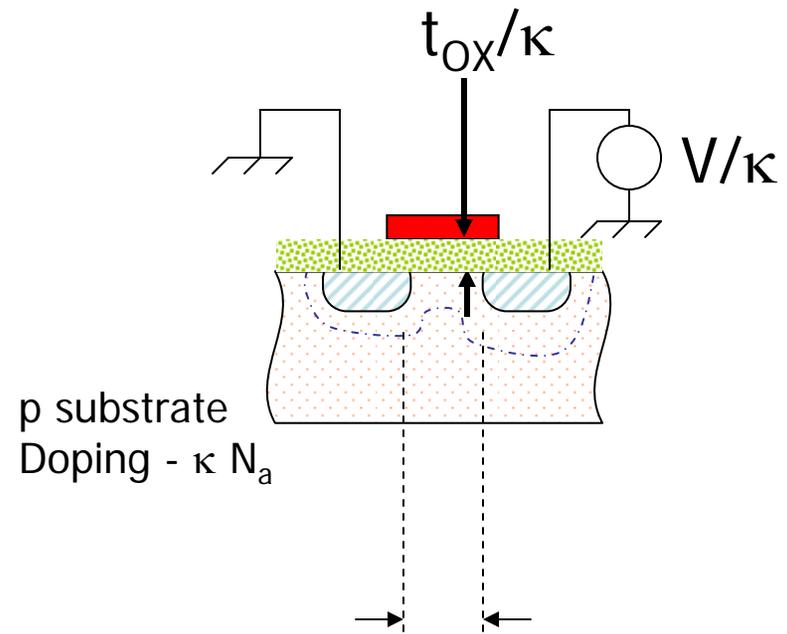


NMOS



Channel Length L

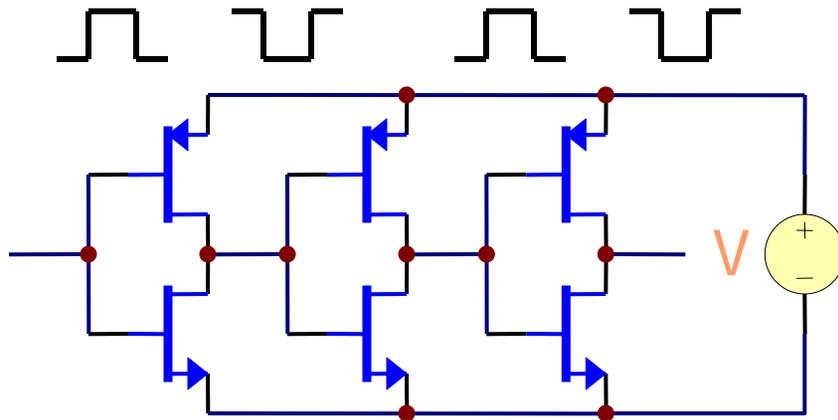
Scaled NMOS



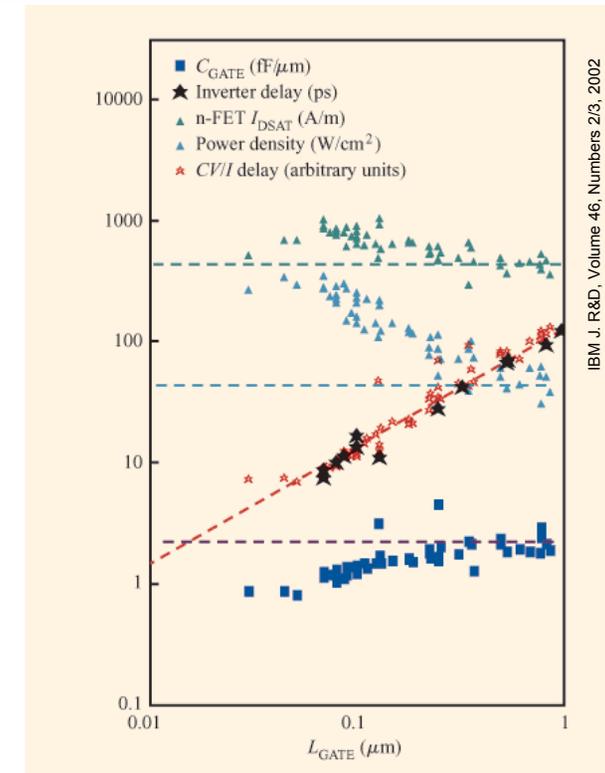
Channel Length L/ κ

Constant Field Scaling

Advantages of Scaling

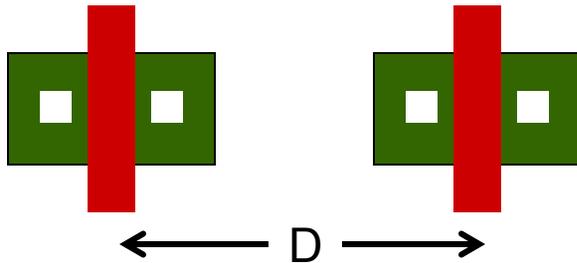


- Speed $\sim C_{\text{GATE}} V_{\text{DD}} / I_{\text{DSAT}} \sim 1/\kappa$
- Circuit Density $\sim 1/A \sim \kappa^2$
- Power/circuit $\sim 1/\kappa^2$
- Power Density (P/A) ~ 1



Great for digital.
Just press the “zoom”
button and shrink your
layout!
Analog is another story

Another Word on Matching



Fluctuations in doping

$$V_T \sim \sqrt{N_a T_{OX}} \propto \sqrt{WLT_{OX}}$$

$$\sigma(V_T) = \frac{A_{V_T}}{\sqrt{WL}} \oplus S_{V_T} D$$

$$A_{V_T} \propto T_{OX}$$

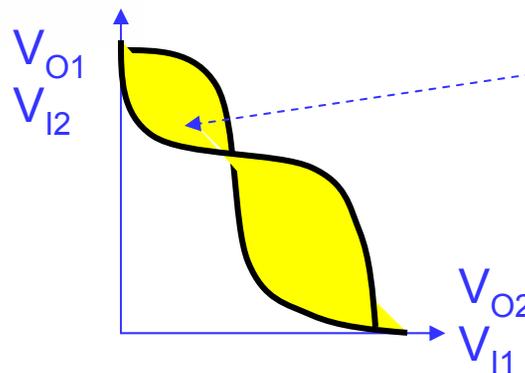
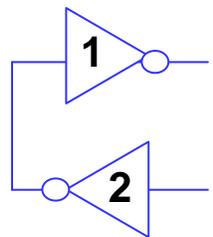
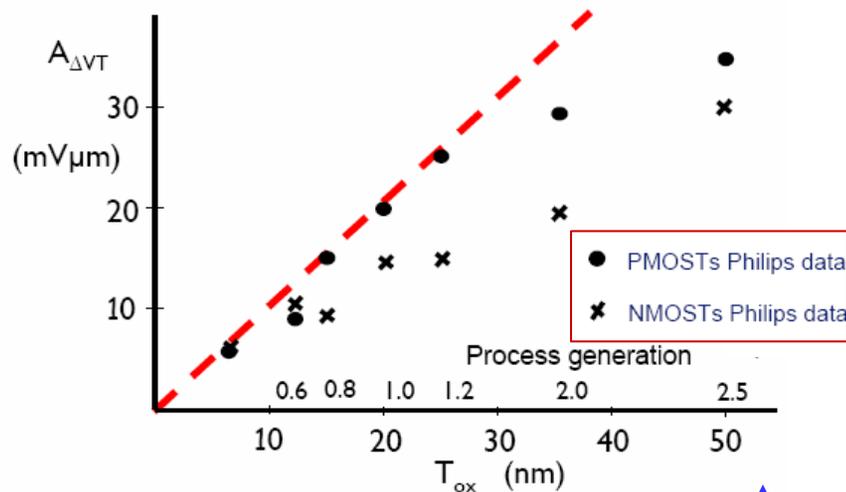
Scaling: $W/L = \text{const.}, L \propto T_{OX}$

But newer technologies don't have

$$A_{V_T} \times L_{\text{MIN}} = \text{const.}$$

Bad for analog, *worse* for digital.

Digital to the rescue?



Mismatch affects this noise margin

What's Next?



Table 59a Single-gate Non-classical CMOS Technologies

Device	Transport-enhanced FETs	Ultra-thin Body SOI FETs		Source/Drain Engineered FETs	
	<p>Strained Si, Ge, SiGe buried oxide Silicon Substrate</p>	<p>BOX</p>	<p>FD Si film S D Ground BOX (<20nm) Plane Bulk wafer</p>	<p>silicide nFET pFET Schottky barrier isolation Silicon</p>	<p>S D Non-overlapped S/D</p>
Concept	Strained Si, Ge, SiGe, SiGeC or other semiconductor; on bulk or SOI	Fully depleted SOI with body thinner than 10 nm	Ultra-thin channel and localized ultra-thin BOX	Schottky source/drain	Non-overlapped S/D extensions on bulk, SOI, or DG devices

Table 59b Multiple-gate Non-classical CMOS Technologies

Device	Multiple Gate FETs				
	N-Gate ($N > 2$) FETs	Double-gate FETs			
		<p>Source Drain</p>	<p>GATE SOURCE DRAIN Si-substrate STI</p>	<p>channel channel independent gates</p>	<p>Gate Gate Drain</p>
Concept	Tied gates (number of channels > 2)	Tied gates, side-wall conduction	Tied gates planar conduction	Independently switched gates, planar conduction	Vertical conduction

“Scaling” and “Death of CMOS” are talks on their own...

Future for IC Design at LBL



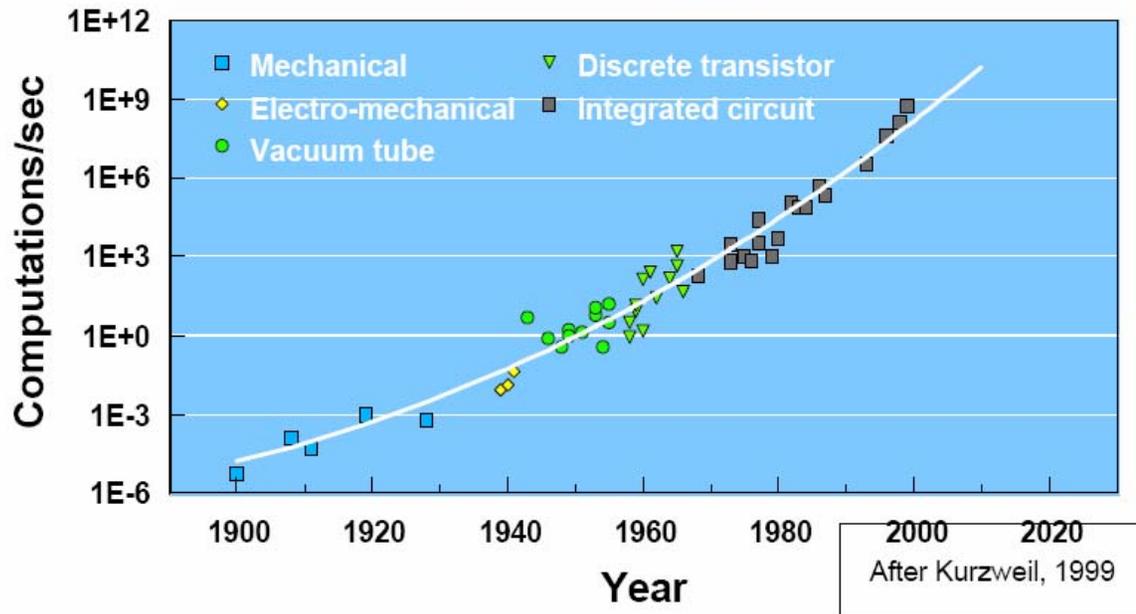
- ◆ Keep the edge in HEP (LHC upgrades, Linear Collider)
- ◆ Astronomy – on the ground and in space
- ◆ Biology and materials – imaging detectors
 - general “smart” detectors – 2D arrays measuring (x, y, E, t)
 - specialized “smart” detectors – e.g. built-in temporal autocorrelations
 - fast detectors for dynamics – “movies”
 - high sensitivity
- ◆ R&D
 - Hybrid pixilated APDs – 2D single photon counting arrays
 - Chemfets – CMOS circuits where the conduction modulation is by (bio) chemical reaction



How did we get to this point?

Growth of computations/second over time

\$1000 buys...



And Acknowledgements + Apologies to the IC+ES Groups



J-F Beche
J-M Bussat
B Holmes
J Johnson
J Joseph
A Karcher
B Krieger
T Stezelberger
J Stirrkinen
C Vu
J-P Walder
A Whichard
H Yaver
S Zimmermann

Topics not suitably addressed

- ◆ CMOS scaling
- ◆ New devices
- ◆ SiGe (and other strained Si) / SOI
- ◆ Analog design problems at fine feature size
- ◆ ...

